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# HYBRID INTEGRATED COMPUTER AIDED DESIGN AND MANUFACTURING

# HUGHES AIRCRAFT COMPANY TUCSON MANUFACTURING DIVISION

HUGHES

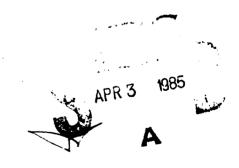
Prepared for:

U.S. ARMY MISSILE COMMAND

**System Engineering Directorate** 

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#### Report DAAH01-D-A002/0006

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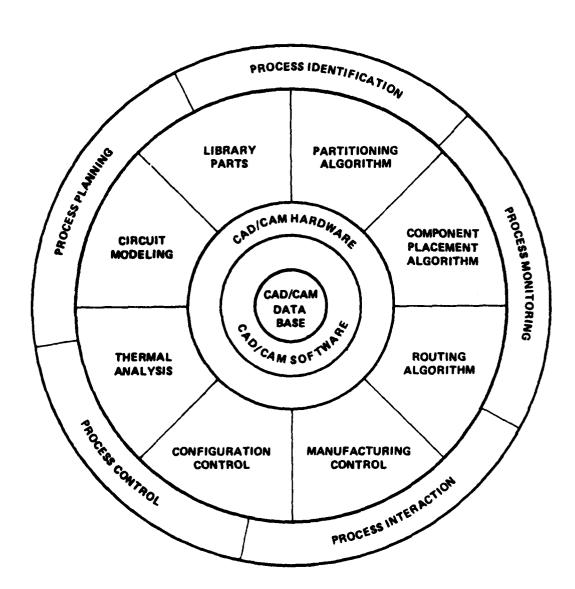
Final Report

Program Manager: Mr. Gordon Little, MICOM

#### Prepared for:

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 $\underline{\textbf{HYBRID}}\,\underline{\textbf{INTEGRATED}}\,\underline{\textbf{C}}\underline{\textbf{OMPUTER}}\,\,\underline{\textbf{A}}\underline{\textbf{IDED}}\,\,\underline{\textbf{D}}\underline{\textbf{ESIGN}}\,\,\underline{\textbf{A}}\underline{\textbf{ND}}\,\,\underline{\textbf{M}}\underline{\textbf{ANUFACTURING}}$ 



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#### - ABSTRACT -

An overview of the design and manufacturing life cycle of a hybrid has been compiled. CAD/CAM interfaces are discussed. Database specifications and types are highlighted. Current and planned MAN TECH programs in the area of hybrid microelectronics technology are summarized. An industry survey has been conducted and analyzed to ascertain those areas where manufacturing technology advancements will have the maximal cost reduction. A HICADAM Systems architecture is proposed utilizing the ICAM modeling methodology of IDEF<sub>O</sub>.

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The design and manufacture of a hybrid microelectronics circuit requires the interfacing of diverse technologies on the leading edge of materials sciences, equipment advancements, and the advent of computer controlled manufacturing processes. Hybrids offer distinct advantages in weight, volume, performance, power, and reliability considerations. They are an efficient interconnect and packaging technology which is cost effective only when their inherent advantages outweigh their relative design and manufacturing costs.

An analysis of the design & manufacturing life cycle of a hybrid has revealed areas where manufacturing technology advancements will reduce the cost of hybrid microelectronics circuits. These advancements may flow from new materials, new processes, and from the introduction of computer integrated manufacturing. Current and planned manufacturing technology enhancement projects are discussed and related to a systems architecture. Projects are proposed for those identified areas where no scheduled projects occur.

Computer integrated manufacturing entails the interfacing of CAD, CAM, CAT, and MIS systems. This interfacing will ensure a closed loop system to design and manufacture hybrids. An architecture which shows these interfaces has been developed.

#### - HYBRID DESIGN PROCESS -

The design process of a hybrid circuit is influenced by many factors. These include the origin of the design stimulus, the extent of the design effort to be undertaken, and the technological constraints. Design evolution, from its conceptualization through its finalization, is a continual tradeoff between these various factors.

The market niche which a firm seeks determines the extent of its design effort. A firm which designs and produces custom hybrids may delve into specific component fabrication. Other firms may use off-the-shelf components exclusively because hybrids are one item in an end product. Military applications generally tend more toward the specialty component markets.

Technological constraints flow from material areas and manufacturing processes. Material constraints include cost, reliability, and physical characteristics. The physical characteristics of certain materials (such as beryllia use in substrates) may dictate extreme environmental controls. The constraints from manufacturing processes include repeatability and mechanical considerations (such as the precise positioning of a large XY table).

The design process of a hybrid is more art than science. The process is very iterative and each subset of activities are strongly interrelated. The three general functions which occur during design are:

- technology selection
- detailed design
- detailed documentation

#### Technology Selection

Technology selection begins the design process for a hybrid.

The designing entity must balance competing forces so that a cost effective hybrid design with the necessary performance characteristics may be realized. A list of factors to be considered includes:

- requirements (performance, reliability, specifications)
- capabilities (equipment, facilities, labor force)
- producibility (component density, yield/design margins)
- material (lead times, number of sources)
- costs (material, equipment, burdened labor, pricing factors)

  The interplay of these decision factors will result in the establishment of boundaries to the conceptualization process.

Hybrid conceptualization may be instituted as a result of a stimulus to create a new product or to modify an existing product. This process can be described as a mixture of direct synthesis, approximate synthesis, and intuitive innovation.

Direct synthesis is the process of using a historical design as a basis for the new design. This is an evolutionary development of a hybrid design.

Approximate synthesis is the process of using two or more historical designs as the basis for the new design. This is a combinatorial evolution of existing designs.

Intuitive innovation is the art and science of developing a completely new circuit design. This is usually the result of a new breakthrough in materials sciences but may result from the advancement of manufacturing technologies.

#### <u>Detailed Design</u>

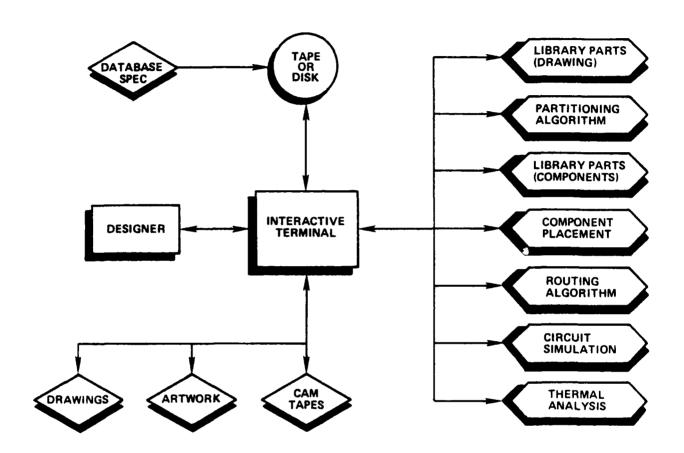
The detailed design process flows from the technology selection decisions. The product is defined logically, electrically, and then physically. This phase of the design process is the most interrelated. Throughout the design steps a designer can use a CAD/CAM system to aid in relating such factors as physical limitations, circuit testability, circuit producibility, and circuit performance specifications. A CAD/CAM system is illustrated in figure 1.

Logical design integrates the conceptual signal flow with the interface requirements generated from circuit partitioning. The logic diagrams can be generated in two fashions. The first features the interaction of a designer and a CAD library of logic symbols. The second uses Boolean Algebra circuit descriptions with a computer to generate the logic diagram. As circuit complexities increase the second procedure becomes more important.

The next step in the design process is the generation of a detailed electrical schematic. The effort involved here is dependent on the detail of the logic diagram. In the best case, the designer needs only to specify part numbers, to add in power/ground requirements, to add signal conditioning circuitry, and to develop a parts list. In the case of a high level block diagram, the designer must develop detailed logic statements to describe each block. These, in turn, will be used in creating the complex schematic. In complex circuits design verification can often only occur through the building of a prototype circuit. In the case of a circuit which uses very large scale integrated devices a macroscopic circuit simulation may be the only viable verification tool.

FIGURE 1.

CAD/CAM SYSTEM ATTRIBUTES



The output of the electrical design consists of documentation, test program information, physical design data, and data for computerized circuit analyses. At this time a schematic may be generated from the CAD database as part of the deliverable documentation. Routing and component placement data is extracted from the CAD system, or manually compiled, and utilized in the physical design process. Crucial test information to be considered includes signal levels, signal types, and the identification of critical test nodes. An illustrative test program generation flow is given in figure 2.

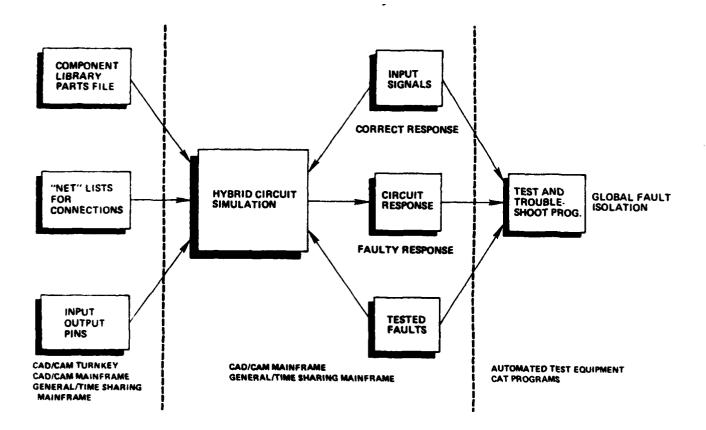
A detailed discussion of circuit design and analysis programs is beyond the scope of this report. The following brief discussion on possible program attributes is included only to add a degree of robustness to the analysis of hybrid microelectronic circuit design.

Circuit design and analysis programs are varied both in their applications and in their complexity. Statistical analyses, such as for component tolerances, may be useful (an example is ASTAP). They may be used to perform AC, DC, and transient analyses (as does ASTAP as well as SPICE2). Design verification and fault simulation for digital circuits is becoming more important as the complexities of circuits increases. TEGAS provides useful tools in these respects. Specialty programs ( such as COMPACT for microwave circuits) may be useful in optimizing specific types of circuits. The future for circuit design and analysis programs lies in providing a mixed bag of tools to aid the designer as opposed to the generation of one all-encompassing analysis program.

The hybrid circuit can now be defined on a physical basis. The preliminary bill of materials, the preplacement criteria, and the physical

FIGURE 2.

### ILLUSTRATIVE TEST PROGRAM GENERATION



size limitations are now intermeshed. This information is supplied to the designer in the form of extracted databases from previously generated CAD databases or from manual compilation efforts. The physical design phase may use a CAD system to determine two types of information. First, placement information is generated consisting of the locations of the various component parts that make up the circuit. Second, based upon this placement of components upon the substrate, the pin-to-pin connections ( using the netlist generated by the logic and electrical schematics ) for each component are made.

Placement algorithms are complex and often designed to perform most efficiently with a particular routing algorithm. Constraints that placement algorithms must face are diverse and complex. Placement must not only consider which components are to be interconnected but also which components are to be connected to external connectors. They must account for component orientation ( to aid the automation of pick and place equipment ), the ultimate circuit configuration, and circuit densities so as to guard against plating difficulties.

Routing the hybrid requires four different types of inputs. The first inputs are the geometrical boundaries of the substrate. These are bounds beyond which no routed signals may exist. The second inputs are general constraints under which the router will be forced to operate.

Typical of these constraints are conductor widths and spacings, the number of layers, via sizes, and maximum flywire lengths. The third set of inputs are extracted from the electrical schematic and are the netlists. This is the pin to pin connection list and specifies which pin of each device is to connected to which pin of any other device or an outside connector.

The fourth type of data is perhaps the most difficult to obtain, particularly for hybrids. This is the physical description of the individual component parts that make up any given hybrid. It includes the exact geometrical location of pins within that part and the component outline. These data vary depending on whether the hybrid is to be chip and wire, TAB/BTAB, chip carrier, or some combination of these techniques. In addition, certain components might be designed with the routed circuitry itself. When this is done the router must be sophisticated enough to automatically incorporate these components into the circuitry or, as is more often the case, the designer must design these devices before the routing process and treat them as component parts. The routing complexity increases dramatically when chip and wire techniques are used and the router must consider the possibility of differing topographies for the various components.

Current component placement and routing algorithms in use for hybrid circuits are modified printed wiring board or VLSIC routing algorithms. The lack of widespread success of these routing algorithms results from important circuit differences which include line spacing, vias which do not pass through the entire substrate, component topography, and external connection requirements.

After placement of components, routing of interconnects, and final gate assignments, sufficient information is available for further circuit analysis. Verification of thermal characteristics, fan out/in power requirements, stray capacitance, testability, and general design rules can be verified. The results of this analysis may dictate changes in the electrical schematic, physical layout, or the design algorithms.

#### Detailed Product Documentation

The last phase of the design process is to detail the product documentation. The test programs, circuit schematics, drawings, artwork masters, and other design documentation are collated and verified. The compilation of the test program is the main task of this phase.

The generation of a precise test program is accomplished to satisfy specific program requirements. Data on circuit response to an input stimulus is tabulated. The input nodes for the test signals are generated such that the confidence interval selected for the test is achieved (minimal alpha and beta errors for a selected confidence interval).

For analog hybrids testing is accomplished by simulating the actual useage in an end-product application. A computer generates the input and monitors the resultant output. While analog hybrid trouble-shooting is currently an art, work is being conducted on a guided probe approach for analog troubleshooting.

Digital hybrids may be tested the same way as analog hybrids but testing is more commonly done on a fault simulation basis. In very complex digital hybrids testing is usually done on a global basis. Specific path sensitization, fault libraries, and guided probes are aids to the troubleshooting of digital hybrids.

There is a continual management review process during the design of a hybrid. Included in this process are program progress, cost tracking, and documentation reviews. The design engineering database will undergo a final review as a complete package prior to being released to the manufacturing engineering functions.

#### - HYBRID MANUFACTURING PROCESS -

The manufacture of hybrid microelectronics has two main generic activities which are substrate fabrication and hybrid assembly. Substrates are typically fabricated through a thin film or a thick film process. The cofiring of ceramics, the use of mid-film technologies, and the use of exotic materials are alternatives to thin and thick film processes. Hybrid assembly consists of the mounting, interconnecting, and packaging of active and passive devices on these substrates. For military applications

#### Thin Film Processes

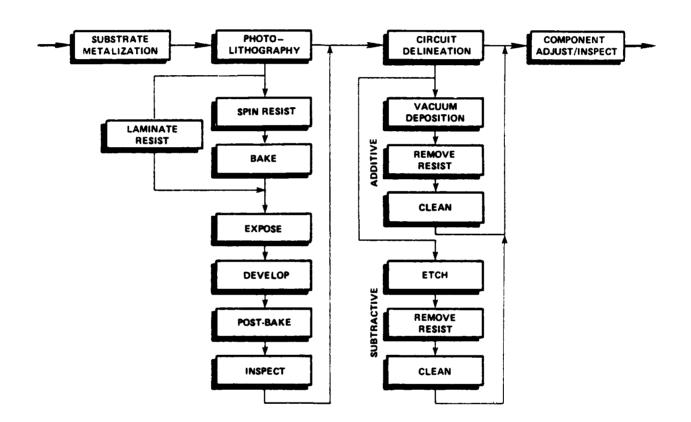
Thin film substrate fabrication has two main functional activities. These are photolithography and circuit delineation. Photolithography defines the desired circuit pattern. Circuit delineation creates the actual film layers. (Refer to figure 3 & figure 4)

Photolithography is the task of applying and developing the resist coating to form the circuit pattern. The resist is applied (via spinning and baking, or lamination) and then exposed. The master artwork ( created from a pattern on rubylith ) is used to expose a specific pattern upon the resist. The resist is developed and washed leaving only the exposed resist pattern on the base substrate. The substrate with the exposed resist is then baked to insure the integrity of the resist pattern.

Circuit delineation can now occur. This process occurs via an additive or a subtractive technique. In an additive process, evaporated material is placed on the substrate by a vacuum deposition technique. The exposed pattern (resist or mask) covers those areas where layering is not to occur. When the deposition process is completed the resist pattern is

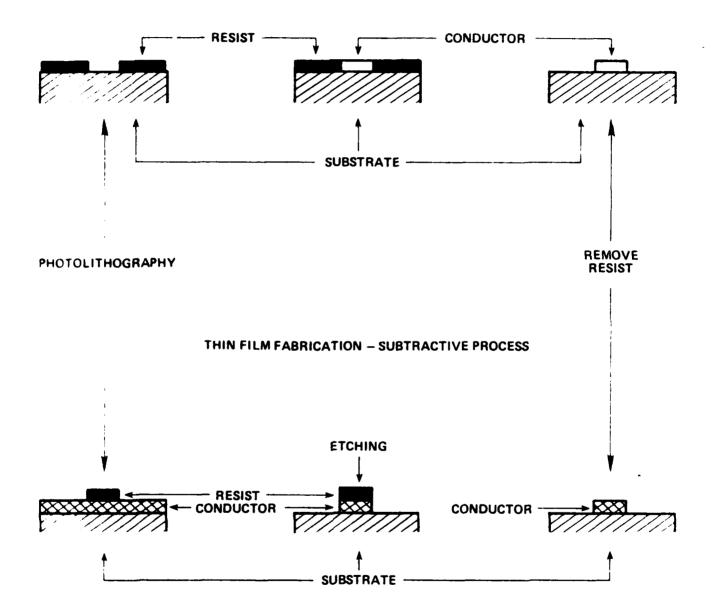
FIGURE 3.

ILLUSTRATIVE THIN FILM PROCESS FLOW



#### THIN FILM FABRICATION

#### THIN FILM FABRICATION - ADDITIVE PROCESS



removed, the substrate is cleaned, and then it is inspected.

In a subtractive process the exposed resist pattern covers those areas which are to remain as part of the circuit. The substrate is placed in an etching solution. This causes the removal of the material on the uncovered surface area. When this process is complete the resist pattern is removed, the substrate is cleaned, and then it is inspected.

Numerous techniques are being used to provide the energy needed to cause the evaporation of the material to be deposited. These include electron beams, ion beams, lasers, heating techniques, and sputtering. The specific film characteristics sought by the user will determine the type of process selected.

Manufacturing constraints (environmental concerns, increased circuit densities, etc.) have fostered the advent of new manufacturing technologies. Examples are the dry etching techniques. Plasma etching (a reactive dry etching) offers reduced chemical hazards but has the problems of repeatability caused by uneven gas flow and thermal gradients. Ion beam milling (a non-reactive dry etching) has enhanced flexibility (angular milling, control of plasma potential, etc.) but suffers from a low etch rate and poor selectivity.

#### Thick Film Processes

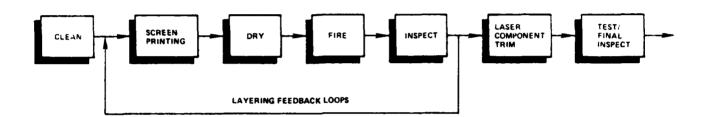
Thick film technology involves the layering of a resistive, a conductive, or a dielectric paste (ink) using a screen printing process.

(Refer to figure 5) The paste (ink) is a composition of minute polycrystalline particles in a thixotropic carrier.

The screen printing process entails the application of a paste through a fine mesh stencil screen onto the substrate. The printed surface

FIGURE 5.

### ILLUSTRATIVE THICK FILM PROCESS FLOW



is then dryed and fired. The conductor layers are inspected and may be tested prior to the continuation of the layering process. Multilayer substrates require the fabrication of vias to serve as interconnects between the conductor layers.

Thick film resistors undergo a trimming operation. This fine adjustment of the resistance values may be done using abrasives or a microprocessor controlled laser.

Substrate testing is generally limited to a continuity test of the conductor layers. Manual probes, a bed-of-nails test head, or a capacitance test may be used to verify continuity.

Numerous factors affect the success, or the failure, of the thick film screen printing process. These include paste rheology, stencil/screen mask fabrication, and the printing technique. To date the screen printing process has not been significantly automated.

#### Cofired Ceramics Process

The cofired ceramics technology may use a sandwiching of tungsten conductor layers between green ceramic sheets. The layers are fabricated, pressed together, and then fired. ( Refer to figure 6 )

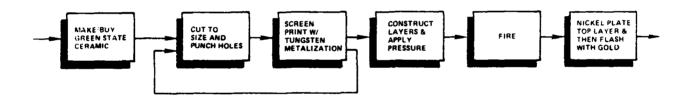
The main problem lies in the shrinkage and the non-repeatability of this shrinkage caused by the firing of the green ceramic. Shrinkages of 12 to 20% are not uncommon. With the advent of tighter spaced lines due to increasing circuit densities, this lack of ability to control the shrinkage prevents the widespread usage of cofired ceramic technology.

#### 

Alternate materials and technologies exist. Porcelanized steel and organic materials can be used as a base for the substrate. A new

FIGURE 6.

# ILLUSTRATIVE COFIRE CERAMICS PROCESS FLOW



mid-film technology can be used to deposit conductor material.

A general overview of the mid-film technique is as follows. Resist is applied to a substrate (by spraying or dipping), a conductor pattern is exposed, and the unexposed resist is washed off. The remaining pattern has a 'sticky' consistency. A conductive powder is applied to this pattern and the substrate is baked. During baking the resist pattern evacuates from the substrate leaving a hardened conductor layer bonded to the substrate.

#### Hybrid Assembly

Hybrid circuits may be assembled under a mixture of line flow and batch mode production operations. The processes described below are illustrative and not definitive.

For a chip and wire assembly the first operations occur in a die attach area. The substrate is cleaned, the die are attached, cured, and the substrate is then inspected for die positioning and integrity. Wirebonding is used for the necessary interconnections. (Refer to figure 7)

The wirebond activities may include the bonding of 2.0 mil, 1.0 mil, and 0.7 mil flywires. The wires are bonded thermosonically (using heat and a 'sonic' scrubbing motion) or by thermocompression (using heat and pressure). A sample and/or a 100% non-destructive wirepull may then be conducted. (Refer to figure 8)

Alternatives to the chip and wire technology are to utilize tape automated bonding/bumped tape automated bonding or chip carrier techniques. (Refer to figure 9) The TAB/BTAB and chip carrier technologies have advantages and disadvantages. Each offers the ability to prescreen the devices prior to attachment to the substrate which will improve yields.

FIGURE 7.

ILLUSTRATIVE CHIP ATTACHMENT

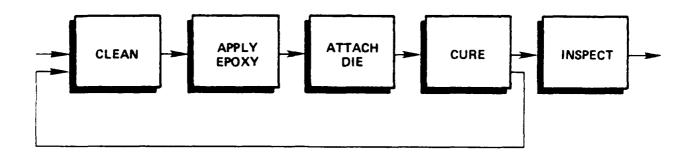
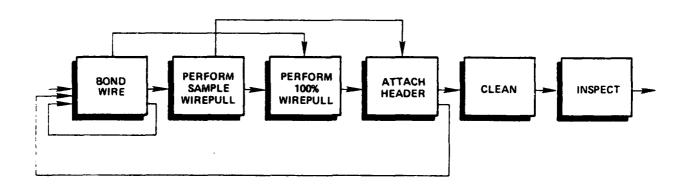
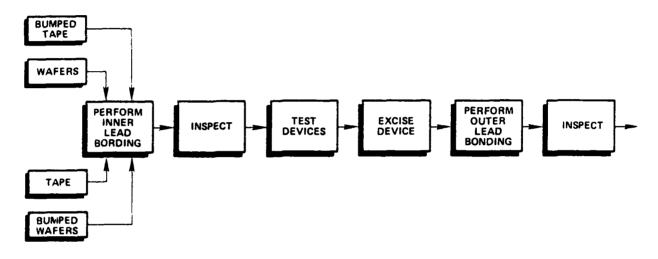


FIGURE 8.

ILLUSTRATIVE WIREBOND PROCESS FLOW



TAB/BTAB ILLUSTRATIVE PROCESS FLOWS



TAB TAPE AUTOMATED BONDING
BTAB BUMPED TAPE AUTOMATED BONDING

The major disadvantages are the loss of in process design flexibility, the availability and standardization of materials, and the increased demand for surface area to connect TAB/BTAB and chip carriers to the substrate.

After mounting the header the hybrid is ready to be packaged.

The leads are attached to the outside connectors and a package configuration is selected. The hybrid may be hermetically sealed in a metal case, it may be plastic encapsulated, or a conformal coating may be applied.

The hybrid ( as a component or as a circuit ) will undergo a certain degree of testing. This testing occurs on a functional basis and on an environmental basis. A functional test is a check on the actual electrical performance of the hybrid whereas an environmental test checks the hybrid under various operating conditions. The environmental tests (also known as screening tests) include the following;

- particle impact noise detection
- stabilization bake
- temperature cycle
- fine leak/gross leak
- burn-in
- acceleration/shock

Hybrids which fail the tests are fault isolated. This process may be manual (as in bench box test positions) or highly automatic (as in digital fault simulation).

A major contributor to hybrid failures are the active devices themselves. Hence, a prescreening program will increase hybrid yields.

TAB, BTAB, and chip carrier technologies offer this aspect. A statistical sample plan can offer the same advantage for a chip/wire technology firm.

#### Computer Aided Manufacturing

Computer aided manufacturing for hybrid microelectronics can be used as a production tool in two basic modes. These are production support and in production automation. Process identification, process monitoring, process interaction, process control, and process planning are examples in these areas. (Refer to figure 10)

The bulk of computer aided manufacturing lies between the process interaction mode and the process control mode. As material handling, equipment automation, and automated test/inspect processes become more advanced and cost effective, the process control mode will become more widespread.

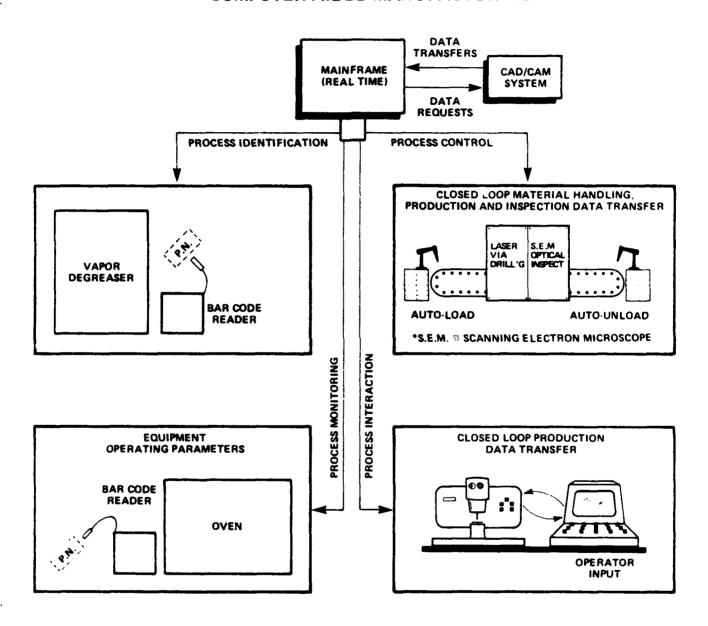
Certain concepts of group technology can be applied in interfacing the design and manufacture of hybrid circuits. Areas of interest include the compilation of component part characteristics, the performance of manufacturing flow analysis, and the generation of planning.

The compilation of part characteristics (via a library parts file) serves a function analogous to that of a coding and classification scheme. The library parts files identify various distinguishing factors (such as die topography, wirebond geographies, costs, wire sizes, etc) which can be used as inputs to a production planning and production operations system as well as the design process.

A manufacturing flow analysis can be utilized to achieve an optimal facilities layout. The component characteristics, when combined with the component counts and equipment specifications, can be used in determining co-location requirements to minimize production costs and times.

FIGURE 10.

## ILLUSTRATIVE USES OF COMPUTER AIDED MANUFACTURING



(2)

Process planning and operator work instructions have been traditionally generated by manual methods, often consisting only of engineering drawings and handwritten instructions. As production levels and hybrid complexities increase these types of documentation and planning are no longer sufficient to accurately produce hybrids. The problem is intensified in the high mix-low volume environment where an operator rarely works on the same module long enough to realize learning curve benefits.

Use of a CAD database to generate process planning and to drive the automated manufacturing operations dictates that the design and manufacturing functions develop a mutual database specification. (Refer to figure 11) Computer generated planning is created interactively and offers significant advantages.

These advantages include variablity in the mode of presentation (traditional paper medium, CRT terminals, video displays, etc.), work instructions which accurately reflect the product engineering, and the automation of certain manufacturing operations and configuration control. One distinct advantage of using computerized planning is the accompodation of die topography variations.

Variations in different vendors' die topographies for electrically equivalent die provides a unique problem, especially in the low volume-high mix environment. This problem is intensified when contractual obligations force 'second source' requirements for unencapsulated chips. These variations in device topographies become particularly onerous at three points in the hybrid life cycle. These points are at constructing the library parts files, at component placement and routing, and in process automation.

Composite library parts may offer a solution to some of the

## FIGURE 11. SAMPLE OF COMPUTER GENERATED ROUTING SHEETS

WESTSUNT PLANNING - ASSEMBLY SEQUENCE & INSTRUCTION SHEET

SHEET 1 OF 4

PROGRAM ---

UNIT CODE ---

PART NAME ---

ASSEMBLY NUMBER ---

096. CHG. LTR. ---

PLANNING REVISION ---

UNIL TIEM NAME --

MODEL

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| 1006  |             | W114    | 1100          | ! MOT WIEFWOAU FUR ME284<br>AMD COMPOSETE GENETICS  |                             |
| 110   |             | 6210    | 41 O          | O / MIL WIREBOND PER MEZIZ<br>AND COMPOSITE GRAPHICS  |                             |
| 129   |             | 5714    | EMSO          | PUNK DESTRUCTIVE SAMPLE WIRE<br>PER APRISA A CUMPUSITE I  |                             |
| 1.20  |             | 5.744   | 41.50         | 100% NUMBERTRUCTIVE WIRE FULL<br>PER MINISK & COMPOSINE GRAPHICS.                                   |                             |
| 210   |             | 8231    | <b>9</b> 0003 | LARRECT WIRESOND ARTHUR SUAL<br>PER FLIM MOA-DOT ARD<br>COMPOSITE ORA THOS.                         |                             |
| 212   |             | 5213    | HOME          | CLIAN MEAGER PIP MEP11 A AU<br>HEAGER WITHOUT PER MEST<br>AMU COMMOSTIE GRACHICS<br>OURE FUR ME224. |                             |

# FIGURE 11. - continued -

ASSY NAME ---ASSY MO.

| OPER.      | REV. | DUPT<br>NO.  | WORK<br>STA: | OPERATION<br>DESCRIPTION                               | Situ HOURS<br>Skir-Oviloo Ru |
|------------|------|--------------|--------------|--|------------------------------|
| <b>214</b> |      | 6214         | H180         | 2 MIL WIREBORD FER MELTS<br>AML CONFOSITE GRAPHECE     |                              |
| 2146       |      | 5214         | H180         | 2 MIL WIREHOND PER MIZE:<br>MPD COMPOSITE UPWENTIES    |                              |
| 216        |      | 621 <b>4</b> | H190         | 100% NUN-DESTRUCTIVE OUR FU<br>PER MP28% % CUMPOSINI O |                              |
| 216        |      | 6.214        | H190         | NON-UESTRUCTIVE Samt F HILL<br>PER MESSA & CONTUSTIE O |                              |
| 230        |      | 8271         | 8504         | LUNCTIONAL TEST.                                       |                              |
| 240        |      | 6243         | H240         | THEAN LIBOMODULE FOR MELLY.                            |                              |
| 150        |      | ଟେଅନ         | მზრა         | INSPECT PRECAP<br>PER FILL CCA-OST.                    |                              |
| 280        |      | 5.21.3       | 11250        | SEAL FER NECTZ   |                              |
| 270        |      | 6013         | 92/20        | TURKTIET PUR MESSO<br>AND OF 270 DRATEFICS             |                              |
| 280        |      | 8231         | 8504         | STABILIZATION FORT.                                    |                              |
| 580        |      | 8234         | 3004         | TEMPERATURE COOK.                                      |                              |
| 300        |      | 8231         | 8504         | MCCELERATION.  |                              |

# FIGURE 11. - continued -

| ASSY NAME             |       |              |  | SHEET A 14 T                 |
|-----------------------|-------|--------------|--|------------------------------|
| OPER. PEV.<br>NO. NO. | DEFT: | WORK<br>Sta. | UPERACION<br>DESCRIPCION                         | STO: HOURS<br>SET UP: 100 Fc |
| 310                   | 3231  | 8504         | FIME LEAK.                                       |                              |
| 320                   | 8231  | 8504         | OROSS LEAK.                                      |                              |
| 330                   | 8231  | 8504         | FIND.  |                              |
| 340                   | 8231  | 3504         | FUNCTIONAL DESTA                                 |                              |
| 350                   | 8231  | 8504         | BUSN 14.   |                              |
| 360                   | 8231  | 8504         | FUNCTIONAL (ES).                                 |                              |
| 3 70                  | 8231  | 9503         | INSPECT FINAL PER PILM<br>MUA-001. HULU FUE CAE. |                              |
| 380                   | 2246  | H380         | MOUNTO NEWS ASSESSES                             |                              |

problems designers, placement algorithms, and routing algorithms face. A composite library part is one that is made up of electrically equivalent devices with very similar topographies. The similarities are rarely great enough to provide meaningful information for wirebonding and die attachment automation. The similarities are sufficient to ensure that when a hybrid is designed using composites, any die of that composite family may be used in the manufacturing process without violating standard manufacturing guidelines specifying chip fit on the pad, maximum wirebond length, wirebond egress angles from the chip, etc. Composite library parts are not a panacea for all problems caused by using multiple vendors for each die, but they do offer a solution to some of the problems. The creation of an 'artifical' intermediate does not come free. Composite libraries endure the same control and maintenance problems common to all library parts. The decision as to which composite a particular venders die belongs to must also be addressed.

#### Material Handing

Hybrid manufacturing involves very specialized and tenacious material handling problems. The size of microelectronic devices and their inherent fragility are two examples of these problems. As the military hybrid uses the most advanced state-of-the-art technology, and thus is the most uniquely configured, standardization is not a viable alternative.

Initial problems are encountered at the device attachment stage. Currently available pick and place mechanisms are not equipped to handle extremely small devices (less than 0.025 inches). Once the device is captured, the same pick and place mechanisms cannot rotate to insure the proper device orientation. This necessitates an extra material handling

step to repackage the devices to the new orientation prior to the pick and place step of device attachment.

Handling substrates during device attachment and wirebonding but prior to sealing represents another problem area. Automated substrate handlers are usually designed to accept one size of substrate. This inflexibility, when combined with the die fragility and the exposed flywires, leads to increased chances for damaging the work in process substrate.

Once sealed, the various package types represent unique handling difficulties. The automation of loading, unloading, and test head fixturing for automation are not feasible at current functional test, screening test, and fault isolation work stations due to package physical characteristics variations.

An ideal material handling system would have several characteristics which apply to most hybrid manufacturing operations. A list of these would include:

- three dimensional movement
- angular motion and circular motion
- very sensitive contact grippers/sensors
- optical character recognition
- interfaced with a CAD/CAM and MIS system
- self-correcting displacement compensation capability

#### - CAD/CAM DATABASE SPECIFICATIONS -

One of the greatest values of a CAD database is that, if properly constructed, it may also serve as the CAM database. Before significant automated use can be made of a database, its contents must be formally defined and structured. The vehicle for this task is the database specification. The hybrid database specification must provide efficiency for design activities as well as sufficiency for automated manufacturing tasks. Such a specification can not be derived without equal input from both the design and the manufacturing activities. A robust database specification must interface between controlling data types, subfigure data types, and the formal layering scheme (Refer to figure 12).

Controlling data represents an information subset which uniquely identifies the generated database of a particular hybrid circuit. This subset of the global database includes information such as part number, effectivity data, revision data, and part-peculiar engineering text.

Subfigure data are inseperable mappings of graphic and non-graphic entities within an engineering database (the intelligence of the database). This subfigure data is usually referred to as library parts files but may be known as cells. As these library parts files will be used throughout the CAD/CAM life cycle of numerous hybrids their integrity must be strictly maintained. The number and types of library parts files used vary from manufacturer to manufacturer. They generally contain data which includes logical, electrical, physical, and management oriented information.

Logical information includes net lists, pad numbers, signal nomenclature, and other signal flow data. This data will be used in verifying the electrical accuracy of the physical layout, as an input to the drawing

FIGURE 12.

## ILLUSTRATIVE DATABASE INTERFACES

| , s<br>e<br>e   | ROGRAM: |                     |
|---|---------|---------------------|
| DRAWING, &  PLY  PRIVES  DEVICES  VIA  LAYER  DIELECTRIC  LAYER  CONDUCTOR  LAYER |         | COMPONENT I.D.      |
| LAYERING SCHEME   |         | LIBRARY PARTS FILES |

of the electrical schematic, and in test program generation.

Physical information is used to generate the artwork, to drive automated manufacturing processes, and as input to the automatic test program. The physical database includes information on component size, length/width of circuit runs, device locations, device orientation, and such things as bond pad locations.

Electrical information kept in library parts files includes operating device characteristics and cross-references to electrically equivalent devices. This database is used as an input to circuit analyses, to the test program generation, to fault isolation programs, and as an aid to in-process design changes.

Management data includes information on production costs. on materials costs, on vender names, supplier names, and inspection criteria.

This management database is useful in configuration tracking, cost tracking, pricing determinations, and other management associated activities.

The layering scheme represents the skeleton of the CAD process. It is a structured hierarchy of information storage and presentation and it establishes the mapping between physical reality and the computer data storages. An example of a layering scheme is detailed in figure 13. Care must be taken to avoid mixing hybrid circuitry layers with software layers.

Work on a macroscopic database management system is being conducted under the Integrated Program for Aerospace-Vehicle Design (IPAD). The IPAD software being developed would augment existing CAD/CAM and MIS systems.

Relational and codasyl database management systems are being reviewed.

FIGURE 13.

## **ILLUSTRATIVE LAYERING SCHEME**

| GRAPHICS SYSTEM<br>LAYER | DESCRIPTION                    | ENTITY TYPE |
|--------------------------|--------------------------------|-------------|
| 1 · 4                    | 1st LAYER CIRCUITRY            | LINE        |
| 5 · 9                    | 1st LAYER DIELECTRIC           | LINE        |
| 10 - 14                  | 1st LAYER VIAS                 | LINE        |
| 15 - 19                  | 2nd LAYER CIRCUITRY            | LINE        |
| 20 - 24                  | 2nd LAYER DIELECTRIC           | LINE        |
| <b>25</b> · 29           | 2nd LAYER VIAS                 | LINE        |
| 30 - 154                 | OTHER LAYERS                   | LINE        |
| 1 <b>55</b> - 159        | LOWEST OHM INK PATTERN         | LINE        |
| 160 - 164                | NEXT HIGHEST OHM INK PATTERN   | LINE        |
| 165 - 174                | OTHER OHM INK PATTERNS         | LINE        |
| 175 - 179                | DEVICES - UNENCAPSULATED       | SUBFIGURE   |
| 180 - 184                | .0007 FLY WIRES                | LINE        |
| 185 - 189                | .001 FLY WIRES                 | LINE        |
| 190 - 194                | .002 FLY WIRES                 | LINE        |
| 195 - 199                | DEVICES - TAPE AUTOMATED BONDS | SUBFIGURE   |
| 200 · 204                | DEVICES - CHIP CARRIER         | SUBFIGURE   |
| 205 - 214                | DRAWING FORMAT                 | SUBFIGURE   |
| 215 - 224                | CONFIGURATION CONTROL FORMAT   | TEXT        |
| 225 - END                | DRAWING IDENTIFICATION DATA    | TEXT        |

IPAD software developements are being directed at:

- executive software
- data management software
- geometry & graphics utility software

A relational database management system (Refer to figure 14) uses a series of 'key' accessed files to track and retrieve information. The success to this type of system lies in the querying structure. This method is easier to comprehend, easier to code but it creates an excess of duplication in the database and consistency problems may occur.

A codasyl database management system ( Refer to figure 15 ) uses pointers at the end of each information location to direct the system to the next data point. This type of system is difficult to code, is difficult for a non-technical user to comprehend, but is computationally faster and reduces data duplication.

IPIP is the IPAD Information Processor. This is an N-level data architecture which uses logical, internal, and mapping schemas. IPIP will permit database access from either a navigational data manipulation (a codasyl based system) or a relational data manipulation (a relational based system). Further information on IPIP is available under NASA contract NAS1-14700, technical plan D6-IPAD-70002-P, subtask D6-IPAD-70038-D, "Manufacturing Data Management Requirements", Boeing Commercial Airplane Company, Seattle, Washington.

FIGURE 14.

# ILLUSTRATIVE RELATIONAL DATABASE MANAGEMENT SYSTEM

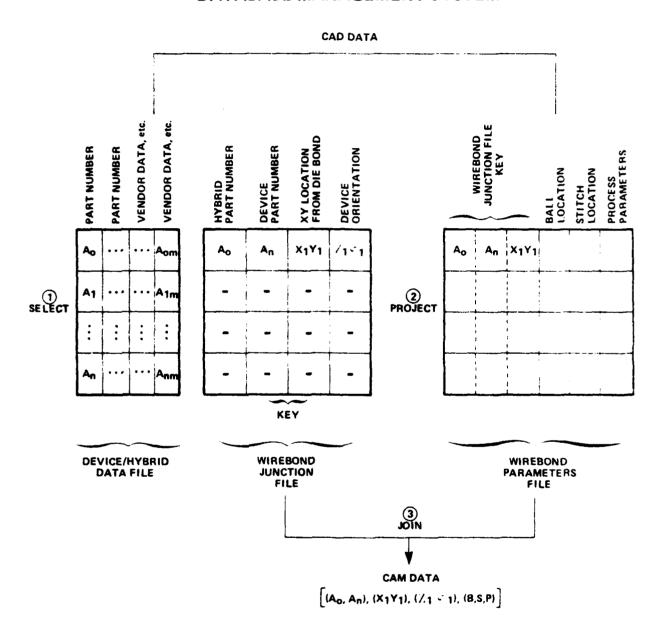
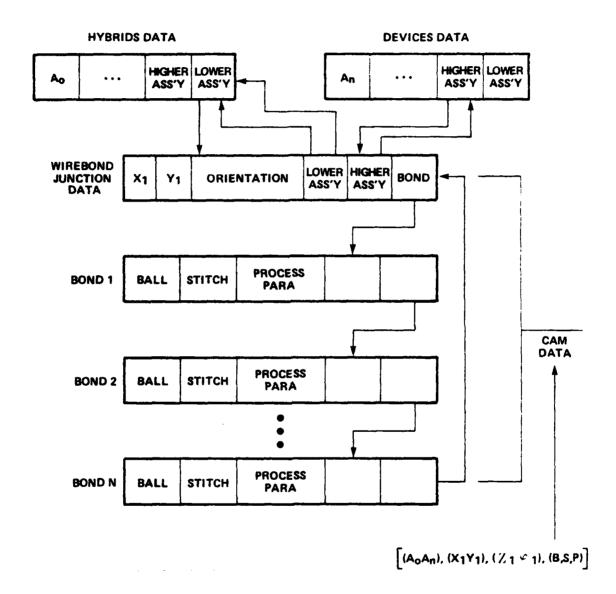


FIGURE 15.

# ILLUSTRATIVE CODASYL DATABASE MANAGEMENT SYSTEM



#### - CURRENT/PLANNED MAN TECH PROJECTS -

A review of current and planned Army, Navy, and Air Force manufacturing methods and technology projects for hybrid circuits has been undertaken. A list of these projects with a cross-reference to the HICADAM architecture is attached as figure 16. As the MAN TECH programs are under a continuous revision process the timeliness of this list should be verified prior to its use. Where possible the listed projects include the project number, or the contract number, the responsible agency, and the estimated year for funding.

A description of each project is beyond the scope of this report.

Numerous sources of information on these projects exist. The most current description of these MAN TECH projects exists in the following reference:

"Overview of Current and Planned Army, Navy, and Air Force MMT Contracts for Hybrid Circuit Technology", Charles E. McBurney, Manufacturing Technology Division, Industrial Base Engineering Activity, Rock Island, Illinois.

This paper will be presented at the Proceedings of the International Society for Hybrid Microelectronics which takes place on October 12 through 14, 1981.

Hughes Aircraft is currently working on several MAN TECH projects in support of a new missile system. Information on these projects will be made available after a contract award occurs.

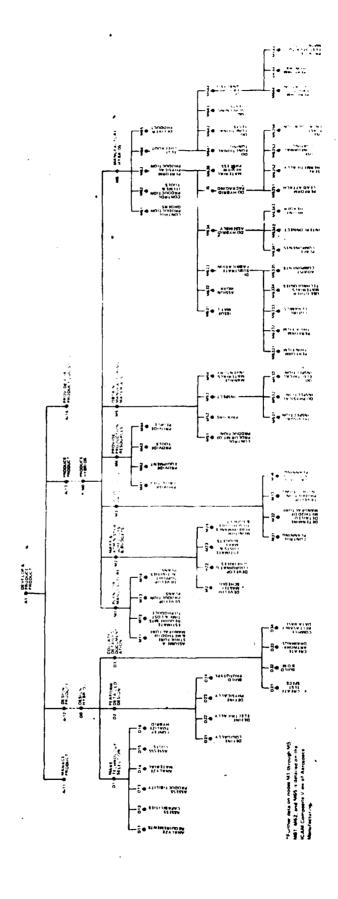
FIGURE 16.

| INDEDIC | MANT | TROU | DDO IFORG |
|---------|------|------|-----------|
| HIDKID  | MAN  | ICCH | PROJECTS  |

|                |                         | HI DRID                       | 1 12 51 7    | 12011          | PROJECTS  |
|----------------|-------------------------|-------------------------------|--------------|----------------|---|
| ARCH .<br>NODE | NODE TITLE              | MAN TECH<br>Number            | YEAR         | RESP.<br>AUTH. | MAN TECH TITLE  |
| 0-0            | DESIGN & MANUFACTURE    | 3-80-1071                     | 1980         | ARMY           | HYBRID INTEGRATED COMPUTER AIDED DESIGN & MANUFACTURING   |
| M-0            | HYBRIDS                 | 3-81-1071                     | 1981         | ARMY           | HYBRID INTEGRATED COMPUTER AIDED DESIGN & MANUFACTURING   |
|                |                         | 18-E-572-1X086101             | 1981         | USAF           | MT FOR ELECTRONICS CAD/CAM ( ECAM )   |
|                |                         | 3-82-1075                     | 1982         | ARMY           | ELECTRONICS COMPUTER AIDED MANUFACTURING ( ECAM )   |
| }              |                         | 18-E-572-1X086101             | 1983         | USAF           | MT FOR ELECTRONICS CAD/CAM ( ECAM )   |
| M5             | OBTAIN MATERIALS        | 3-81-1060                     | 1981         | ARMY           | ELECTRICAL SCREENING AND TEST OF CHIPS  |
|                |                         | 3-82-1091                     | 1982         | ARMY           | ELIMINATION OF PRECIOUS METALS IN MICROCIRCUITS   |
|                |                         | 3-81-1059                     | 1981         | ARMY           | ELECTRICAL VERIFICATION & BURN-IN OF HYBRID CHIPS   |
| M633           | DO SUBSTRATE            | DNA-81016                     | 1981         | NAVY           | AUTOMATIC MICROSTRIP CIRCUIT BOARD FABRICATION  |
|                | FABRICATION             | DNE-00137                     | 1981         | NAVY           | MICROWAVE STRIPLINE CIRCUITRY PROCESSES   |
|                |                         | 3-82-1092                     | 1982         | ARMY           | AUTOMATIC TESTING OF SUBSTRATES   |
| M6331          | PERFORM THIN FILM       | DNA-00675                     | 1979         | NAVY           | HIGH OHMS PER SQUARE THIN FILM RESISTORS  |
|                |                         | F-81-9835                     | 1981         | ARMY           | INTEGRATED THIN FILM TRANSISTOR DISPLAY   |
|                |                         | F-82-9835                     | 1982         | ARMY           | INTEGRATED THIN FILM TRANSISTOR DISPLAY   |
|                |                         | DNA-00674                     | 1982         | NAVY           | MULTIPLE SHEET RESISTANCE THIN FILMS  |
|                |                         | DNA-006XX                     | 1982         | NAVY           | MICROBRIDGE CROSSOVERS FOR THIN FILM HYBRIDS  |
| ; l            |                         | DNA-006ZZ                     | 1983         | NAVY           | MONOMER FILMS FOR THIN FILM HYBRIDS   |
| } <u> </u>     |                         | DNE-034YY                     | 1983         | NAVY           | EXTRA HIGH FREQUENCY IC'S ( THIN & THICK FILM CIRCUITRY )   |
| M6332          | PERFORM THICK FILM      | 3-79-3146                     | 1979         | ARMY           | HIGH DENSITY MULTILAYER THICK FILM HYBRID MICROCIRCUITS   |
|                |                         | DNA-00053                     | 1979         | NAVY           | COMPUTERIZED THICK FILM PRINTER   |
|                |                         | 3-80-3435                     | 1980         | ARMY           | SIMPLIFICATION OF HIGH POWER THICK FILM HYBRIDS   |
|                |                         | H-81-9552                     | 1981         | ARMY           | THICK FILM CONDUCTIVE NETWORKS  |
|                |                         | DNE-034YY                     | 1483         | NAVY           | EXTRA HIGH FREQUENCY IC'S ( THIN & THICK FILM CIRCUITRY )   |
| M6341          | PLACE COMPONENTS        | 3-79-3219                     | 1979         | ARMY           | AUTOMATIC POLYMER ATTACHMENT PRODUCTION METHODS   |
|                |                         | 3-80-3219                     | 1980         | ARMY           | AUTOMATIC POLYMER ATTACHMENT PRODUCTION METHODS   |
|                |                         | F33615-80-C-5053              | 1980         | USAF           | MT FOR SUBSTRATE ASSEMBLY WITH HERMETIC CHIP CARRIERS   |
|                |                         | 3-81-1076                     | 1981         | ARMY           | PATTERN RECOGNITION OF COMPONENTS FOR HYBRIDS   |
|                |                         | 3-82-1076                     | 1982         | ARMY           | PATTERN RECOGNITION OF COMPONENTS FOR HYBRIDS   |
| H6342          | INTERCONNECT            | DNS-00481                     | 1977         | NAVY           | BUMPED TAPE AUTOMATIC BONDING   |
|                |                         | F33615-77-C-5283              | 1977         | USAF           | MT FOR HERMETIC CHIP CARRIER PACKAGING (HUGHES)   |
|                |                         | F33615-77-C-5158              | 1977         | USAF           | MT FOR HERMETIC CHIP CARRIER PACKAGING (RCA)  |
|                |                         | F33615-78-C-5158              | 1978         | USAF           | MT FOR HERMETIC CHIP CARRIER PACKAGING (TI)   |
|                |                         | F33615-78-C-5147              | 1978         | USAF           | MT FOR LOW COST CHIP CARRIERS   |
|                |                         | DNS-00712                     | 1980         | NAVY           | HERMETIC CHIP TAPE CARRIER  |
|                |                         | F-33615-80-C-5010             | 1980         | USAF           | MT FOR HI-RELIABILITY WIREBONDING IN HYBRID CIRCUITS  |
|                |                         | 08-E-504-1B084130             | 1981         | USAF           | SUBSTRATE ASSEMBLY WITH HERMETIC CHIP CARRIERS  |
|                |                         | H-82+5005                     | 1982         | ARMY           | SEALED CHIP TAPE CARRIER FOR HYBRIDS  |
| M635           | DO HYBRID PACKAGING     | F33615-80-C-XXXXX             | •            | USAF           | HIGH SPEED DIGITAL PROCESSOR PACKAGING TECHNIQUES   |
|                |                         | 11-E-503-1A084260             | 1981         |                | HIGH SPEED DIGITAL PROCESSOR PACKAGING TECHNIQUES   |
|                |                         | 11-E-503-1A084260             |              | USAF           | HIGH SPEED DIGITAL PROCESSOR PACKAGING TECHNIQUES   |
|                |                         | 28-E-583-2A08XXXX             |              | į.             | HIGH RELIABILITY PACKAGING  |
|                |                         | 28-E-583-2A08ZZZZ             | 1983         | USAF           | HIGH RELIABILITY PACKAGING  |
| ,,,,,,,,       | PERFORM LEAD ATTACH     | DNA-00679                     | 1977         | NAVY           | AUTOMATED HYBRID LEAD ASSEMBLY  |
|                | SEAL HERMETICALLY       | 3-82-1095                     | 1982         | ARMY           | AUTOMATIC SEALING OF HYBRIDS  |
|                | PERFORM FAULT ISOLATION |                               | 1980         | ARMY           | DIGITAL FAULT ISOLATION FOR HYBRIDS   |
| M6442          | PERFORM REWORK          | 3-79-3438                     | 1979         | İ              | DELIDDING PARALLEL SEAM SEALED HYBRID PACKAGES  |
|                |                         | DNA-0C253                     | 1980         | NAVY           | DELIDDING & RESEALING OF HYBRID MICROCIRCUITS   |
| OTHER          |                         | 3-79-3410                     | 1979         | ARMY           | PRODUCTION METHODS FOR HEAT PIPES FOR HYBRIDS/LSI   |
|                | Į.                      | 3-80-3436                     | 1980         | ARMY           | DEVELOPEMENT OF CERAMIC - INCUIT BOARDS & LARGE AREA HYBRIDS  |
|                |                         | 3-80-1024<br>3-80-7319        | 1980<br>1980 | ARMY           | RF STRIPLINE HYBRID : OMFONENTS<br>DIGITALLY ADDRESSABLE MU'TI-LEGEND DISPLAY SWITCH                |
|                |                         | 3-81-1066                     | 1981         | ARMY           | ADDITIVE SINGLE & MULTILAYER HYBRID CIRCUITRY   |
| ì              |                         | 3-81-7319<br>N62269-81-C-0067 | 1981<br>1981 | NAVY           | DIGITALLY ADDRESSABLE MULTI-LEGEND DISPLAY SMITCH<br>BROADBAND SOLID STATE HIGH POWER RF AMPLIFIERS |
|                |                         | 3-82-3081                     | 1982         | ARMY           | RADAR MONOPULSE SEEKER USING PT & STRIPLINE TECHNIQUES  |
| 1              | }                       | 3-82-1066<br>1-82-7319        | 1982<br>1982 | ARMY           | ADDITIVE SINGLE & MULTILAYER HIBIRD CIRCUITRY DIGITALLY ADDRESSABLE MULTI-LEGEND DISPLAY SWITCH     |
| •              | ]                       | H-82-5114                     | 1982         | ARMY           | MINI-LASER TRANSMITTER MODULE   |
| OTHER          | <u> </u>                | 3-83-1024                     | 1983         | ARMY           | RF STRIPLINE HYBRID COMPONENTS  |

FIGURE 14. supplement -

O.



FRIODILL OF GOVERNMENT EXPENSE

| 1. What                 | ,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,     | or imary cod product   | t application ?   |  |
|-------------------------|---|--|---|--|
| 5 respon                | nses 🔀                                      | aerospac∈  |   |  |
| 3 respo                 | nses 🔀                                      | communication  |   |  |
| 1 respon                | nse 🔀                                       | computer   |   |  |
|                         |   | consumer   |   |  |
|                         |   | industrial   |   |  |
|                         |   | instrumentation,   | , test equipment  | •  |
| : respo                 | nse 🛮                                       | other, please sp   | pecify:   |  |
|                         |   |  | •   |  |
| ° What                  | i   | nrimoro icualuaman   | nt with hybrid circuits   | 2  |
| . what                  |   | semiconductor pt   | -   | •  |
| 1 respo                 | nse* 🔀                                      | ·  | oment for hybrid circuit  | ٠, د   |
| -                       | nses* 🔀                                     | •  | esign-manufacture   |  |
|                         | nses* 🔀                                     | •  | design/manufacture to su  | ipport end product                                       |
| 1 10390                 |   | other, please sp   |   | ••   |
| ∺ one f                 | irm respon                                  | nded to doing each   |   |  |
|                         |   |  |   |  |
|                         |   |  | to support the design a   | ind manufacture of                                       |
|                         | type of<br>Fir usts                         |  | to support the design a   | and manufacture of  Computer Aided Macut.                |
|                         |   | ?  | Computer Aided Design   | Computer Aided Massi.                                    |
|                         | cir uits                                    | ?  |   | ·  |
|                         | turnkey  dedicate ceneral                   | ;<br>system  | Computer Aided Design   | Computer Aided Massi.                                    |
|                         | turnkey  dedicate ceneral'                  | system d mainframe time sharing  | Computer Aided Design 5 responses   | Computer Aided Massi.                                    |
|                         | turnkey  dedicate ceneral main other, p     | ?<br>system<br>d mainfram⊬<br>time sharing<br>frame  | Computer Aided Design 5 responses - 3 responses   | Computer Aided Maint.  4 responses                       |
|                         | turnkey  dedicate ceneral main other, p     | system d mainframe time sharing frame lease specity:   | Computer Aided Design 5 responses - 3 responses -   | Computer Aided Main:.  4 responses  -  1 response (test) |
| hvbrid                  | turnkey  dedicate  ceneral'  main  other, p | system  d mainframe  time sharing frame  lease specity :   | Computer Aided Design 5 responses - 3 responses - 2 responses   | Computer Aided Main:.  4 responses  -  1 response (test) |
| hvbrid                  | turnkey  dedicate ceneral' main other, p    | system d mainframe time sharing frame lease specity: ANUAL   | Computer Aided Design 5 responses - 3 responses - 2 responses   | Computer Aided Main:.  4 responses  -  1 response (test) |
| hvbrid                  | turnkey  dedicate ceneral' main other, p    | system  d mainframe  time sharing frame  lease specity :  ANUAL  atabase generated  a released CAD o | Computer Aided Design 5 responses - 3 responses - 2 responses from : database                                   | Computer Aided Main:.  4 responses  -  1 response (test) |
| hvbrid  4. Is v 5 respo | turnkey dedicate ceneral' main other, p M.  | system d mainframe time sharing frame lease specity: ANUAL atabase generated a released CAD of       | Computer Aided Design 5 responses - 3 responses - 2 responses from : database database                          | Computer Aided Main:.  4 responses  -  1 response (test) |
| hvbrid                  | turnkey dedicate ceneral' main other, p M.  | system  d mainframe  time sharing frame  lease specity :  ANUAL  atabase generated  a released CAD o | Computer Aided Design 5 responses - 3 responses - 2 responses  from : database database database factormulation | Computer Aided Main:.  4 responses  -  1 response (test) |

Figure 18.

If you have a computer system to support the design of hybrid circuits please check the capabilities which you use & the system where they reside.

| <pre>capability</pre>             | CAD/CAM<br>turnkey | CAD/CAM<br>maintrame | general TS<br>main!ram | other |
|-----------------------------------|--------------------|----------------------|------------------------|-------|
| treary parts (drawing symbols)    | 5                  | 2                    | 0                      | (     |
| library parts ( component specs.) | 5                  | 1                    | 0                      | 1     |
| partitioning algorithm            | 0                  | - 0                  | 1                      | ;     |
| component placement algorithm     | ()                 | 1                    | 2                      | 1     |
| routing algorithm                 | 1                  | 2                    | 1                      | 1     |
| .irouit simulation                | 1                  | 0                    | 5                      | 1     |
| thermal analysis                  | v                  | 1                    | 4                      | 1     |
| test program generation           | 1                  | 0                    | 1                      | 3     |
| configuration control             | 1                  | 1                    | 2                      | 1     |
| other, please specify : Artwork & | 3                  | 0                    | 0                      | 0     |
| Design Rules Check                |                    | <u> </u>             |                        |       |

NO RESPONSE: 2

Please check the appropriate box for the following data.

| algorithm               | internally developed | commersially avail. | other |
|-------------------------|----------------------|---------------------|-------|
| partitioning            | 4                    | 0                   | 11    |
| component placement     | 4                    | 1                   | 1     |
| routing                 | 3                    | 2                   | 1     |
| circuit simulation      | 2                    | 6                   | 1     |
| circuit analysis        | 3                    | 4                   | :     |
| test program generation | 3                    | 1                   |       |
| other, please specify : | 3                    | 2                   | 6     |
|                         |                      |                     |       |

NO RESPONSE : 2

 numbers inside the boxes represent the respondents (total) who answered that question or checked a box

Figure 19. Solves the percentage of total design time dedicated to each task.

| capability              | less than |     |     |     |       |     |    |  |
|-------------------------|-----------|-----|-----|-----|-------|-----|----|--|
| Capability              | 20%       | 40% | 60% | 80% | u()°, | 451 | 10 |  |
| -chematic generation    | 7         | 3   | 0   | O O | 0     | ()  | Ü  |  |
| partitioning            | 6         | 0   | U   | 0   | 0     | 0   | Ö  |  |
| component placement     | 5         | 1   | 2   | 0   | 0     | ('  | O  |  |
| routing                 | 5         | 3   | O   | 0   | 0     | ()  | C  |  |
| test program generation | 5         | 1   | С   | 0   | 0     | Ç   |    |  |
| configuration control   | 7         | 0   | O   | 0   | 0     | С   | С  |  |
| other, please specify:  | 4         | 0   | 0   | 0   | 0     | Q.  | O  |  |
|                         |           |     |     |     |       |     |    |  |

Fig. Please rate the effectiveness of those capabilities as to degree of task accomplished automatically.

| capability              | -less than - |     |     |     |     |      |      |  |
|-------------------------|--------------|-----|-----|-----|-----|------|------|--|
| Capability              | 20%          | 40% | 60° | 80% | 90% | (, ε | 1600 |  |
| schematic generation    | 0            | 0   | 1   | 1   | 1   | 1    |      |  |
| partitioning            | 1            | 0   | 0   | 1   | 0   |      | ()   |  |
| component placement     | 2            | O   | 3   | ()  | 0   | l o  | Ó    |  |
| routing                 | 1            | 0   | 0   | 1   | 2   | ij.  | (i   |  |
| test program generation | 1            | 2   | 0   | 0   | 0   | 41   | 11   |  |
| configuration control   | 2            | 0   | 0   | 1   | 0   | Ċ    |      |  |
| ther, please specify:   | 0            | 0   | 0   | v   | 1   | 1    | 2    |  |
|                         |              |     |     |     |     |      |      |  |

NO RESPONSE : 4

Please rate the percentage of design time per task required to manually complete the task.

| capability                            |       |     |     | less than |     |     |     |
|---------------------------------------|-------|-----|-----|-----------|-----|-----|-----|
| , , , , , , , , , , , , , , , , , , , | 2(14, | 40% | 60% | 80".      | 90% | 7,  |     |
| schematic generation                  | 7     | 1   | υ   | 0         | o   | · · | 1   |
| partitioning                          | 5     | n   | 0   | 0         | 0   | Ċ   | 2   |
| component placement                   | 5     | t   | 1   | 1         | 0   | : ) | 2   |
| routing                               | 7     | 0   | 0   | 1         | 0   | 0   | 2   |
| test program generation               | 2     | 2   | 3   | ()        | 0   | ()  | 1   |
| configuration control                 | 5     | O   | 1   | 0         | 0   | n   | 1   |
| other, please specify:                | 4     | O   | 0   | 0         | 0   | . 1 | . 1 |

- numbers inside the boxes represent the total boxes checked by the response

-actual numerical responses are inside the boxes-

Please rank the following processes for cost contribution from 1 to 12 with process #1 having the greatest cost contribution.

|                                   | equipment   | material   | process     |
|-----------------------------------|-------------|------------|-------------|
| photolithography                  | 3,6,5       | 4,2,6      | 1,11,10,7   |
| additive circuit delineation      | 4,7         | 4,1        | 7,12        |
| subtractive circuit delineation   | 5,11,7      | 3,5        | 8,10,4,8    |
| screen printing                   | 2,7,6,6,6   | 1,2        | 6,7,5,5     |
| laser trimming                    | 1,1,2,7     | 8          | 5,9,8,11    |
| device attachment(TAB,BTAB,CC,etc | 2,8,8,4,2   | 3,8,3      | 5,4,6,3,4   |
| wirebonding                       | 3,9,4,3,4,3 | 1,5,4      | 6,3,5,2,3   |
| wirepulling                       | 2,11,9,5    | 1,7,10     | 3,12,3,7,10 |
| inspection                        | 5,10,10,8,1 | 4// 1,6,12 | 5,9,2,9,9,2 |
| functional testing                | 6,2,2,1,1   | 1,10,7     | 7,2,4,1,2   |
| tault isolation                   | 4,3,3,1,3,5 | 2,11,9     | 4,11,1,1,1  |
| material handling                 | 2,12,12     | 2,9,11     | 10,10,8,6,6 |

Please rank the following factors for possible technological advancement from manufacturing technology developments with 1 being the most promising and 12 being the least promising.

|                                   | equipment    | material    | process      |
|-----------------------------------|--------------|-------------|--------------|
| photolithogr <b>ap</b> hy         | 6,12,7,12    | 4,5,2       | 4,12,4       |
| additive circuit delineation      | 7,11,5,11    | 5,2,3       | 6,11,1       |
| subtractive circuit delineation   | 8,9,6,10     | 6,6,4       | 10,10,10     |
| screen printing                   | 4,5,10,4,4,6 | // 3,1,1,1  | 2,3,8,5      |
| laser trimming                    | 2,8,12,7     | 7,8         | 5,9,12       |
| device attachment(TAB,BTAB,CC.etc | 2,3,4,1,1    | 8,3,3       | 4,11,3,3     |
| wirebonding                       | 10,4,5,2,2,2 | ,5//6,2,4,5 | 8,7,4,2      |
| wirepulling                       | 7,12,6,11,8  | 12,9        | 5,12,6,11    |
| inspection                        | 3,9,2,3,1,3  | 2// 11,11,1 | 2//6.1.2.4.2 |
| functional testing                | 4,1,7,9,1,9  | 1,9,7       | 5,2,7,5      |
| fault isolation                   |              | //11.10.10  | 4.9.1.7      |
| material handling                 | 1.11.3.8.4   |             | 1.8.5.8      |

Figure 21.

data entry format : response average ( number of responses )

15. Please rank the following processes for cost contribution, them I to 12 with process #1 having the greatest cost contribution.

|                                   | equipment | material | process |
|-----------------------------------|-----------|----------|---------|
| photolithography                  | 4.67(3)   | 4.00(3)  | 7.25 1  |
| additing direction                | 5.50(2)   | 2.50(2)  | 9,50 1  |
| subtractive circuit delineation   | 7.67(3)   | 4.00(2)  | 7.500-  |
| screen printing                   | 5.40(5)   | 1.50(2)  | 5.75(4) |
| laser trimming                    | 2.75(4)   | 8.00(1)  | 8.25(4) |
| device attachment(TAB,BTAB,CC,etc | 4.80(5)   | 4.67(3)  | 4.40(5) |
| wirebonding                       | 4.33(6)   | 3.33(3)  | 3.80(5) |
| wirepulling                       | 6.75(4)   | 6.00(3)  | 7.00(5) |
| inspection                        | 6.00(6)   | 6.33(3)  | 6.00(6) |
| tunctional resting                | 2.40(5)   | 6.00(3)  | 3.20(5) |
| tault isolation                   | 3.80(5)   | 7.33(3)  | 3.60(5) |
| material handling                 | 8.67(3)   | 7.33(3)  | 8.00(5) |

Please rank the following factors for possible technological advancement from manufacturing technology developments with I being the most promising and 12 being the least promising.

|                                      | equipment | material | process  |
|--------------------------------------|-----------|----------|----------|
| photolithography                     | 9.25(4)   | 3.67(3)  | 6.67(3)  |
| additive circuit delineation         | 8.50(4)   | 3.33(3)  | 6.00(3)  |
| subtractive circuit delineation      | 8.25(4)   | 5.33(3)  | 10.00(3) |
| screen printing                      | 5.50(6)   | 1.50(4)  | 4,50(4   |
| laser trimming                       | 7.25(4)   | 7.50(2)  | 8.67(3   |
| device attachment(TAB, BTAB, CC, etc | 2.20(5)   | 4.67(3)  | 5.25(=   |
| wirebonding                          | 4.29(7)   | 4.25(+)  | 5.25(-   |
| wirepulling                          | 8.80(5)   | 10.30(2) | 8.50(4   |
| inspection                           | 3.29(7)   | 11.33(3) | 4.00(5)  |
| functional resting                   | 5.16(5)   | 9.49(3)  | 5.00(4)  |
| fault isolation                      | 4.67(6)   | 10.33(2) | 5.25(4)  |
| material handling                    | 5.40(5)   | 9.ig (3) | 5.50(4)  |

## Figure 22.

## MANUAL RESPONSES ONLY !

12. Please denote the degree of automation used for the following processor.

 $\underline{M}$  = manual:  $\underline{S}$  = sem.-automatic:  $\underline{A}$  = automatic:

|                               | monitoring | load,<br>unload | positioning | process<br>control | inspect  | 1081       |
|-------------------------------|------------|-----------------|-------------|--------------------|----------|------------|
| photoresist application       | 1          | 3               | 3           | 3                  |          | -          |
| photoresist exposure          | ı          | 3               | 2           | 2                  | 3        |            |
| photoresist develop.          | 1          | 3               | 3           | 3                  | 3        | • <u>1</u> |
| vacaum s <b>v</b> stem- vapor | -          | 1               | l           |                    | 1        |            |
| i dum system- sputter         | -          | 2               | 1           | -                  | 2        | 1          |
| etching system                | 3          | 4               | 4           | 4                  | <b>-</b> |            |
| s reen printing               | Ó          | 4               | 3           | 7                  | n i      | -          |
| la-er trimming                | 1          | 5               | -           | l                  | <u>.</u> | -          |
| juntinuity tester             | -          | 4               | 2           | 1                  | _        | !          |
| lie attach                    | 5          | 6               | 5           | 6                  | - :      |            |
| Tipe of . bording             |            | 1               | _           | _                  | :        | _          |
| comp tape auto, bonding       | _          | =               | _           | -                  | 1        | -          |
| nip carrier bonding           | 1          | 2               | 1           | _                  | 3        |            |
| inner lead bonding            | -          | 1               | -           | 1                  | 1        |            |
| outer lead baiding            | -          | -               | -           | -                  | ;        | 1          |
| w rehead-for chip/wire        | 3          | 4               | 2           | 1                  | 4        |            |
| $x, t \in p \cup M$           | 3          | 5               | 5           | 3                  | 4        | •          |
| . pection                     | ń          | 5               | 4           | 5                  | 7        | ·          |
| -aling                        | 3          | 5               | 2           | 3                  |          |            |
| rom tional test               | 4          | h,              | 3           | 3                  |          |            |
| insit isolation-analog        | <u>:</u>   | ′ <b>.</b>      | <u>:</u>    | 4                  | ,        |            |
| rasit i siatum=digital        | 2          | 2               | 2           | 2                  |          |            |
| Talak testi                   | 3          | 7               | 4           | 3                  | -        |            |
| competiture cycle             | 1          | 6               | 2           | 1 1                |          | -          |
| rabilization take             | }          | ?               | }           | -                  | ,        |            |
| rore-up test                  | !          | 7               | 3           | .1                 |          |            |
| other, please specify:        | -          |                 | -           | _                  | _        | -          |

## Figure 23.

## SEMI-AUTOMATIC RESPONSES ONLY !

12. Please denote the degree of automation used for the following processes.

 $\underline{M}$  = manual:  $\underline{S}$  = semi-automatic:  $\underline{A}$  = automatic:

|                         | monitoring | load/<br>unload | positioning | process<br>control | inspect | test  |
|-------------------------|------------|-----------------|-------------|--------------------|---------|---|
| photoresist application | 2          | _               | _           | 1                  | _       | -   |
| chotoresist exposure    | 2          | _               | i           | 1                  |         |   |
| protoresist develop.    | ì          | -               | -           | -                  | 1       | <u>· -                                     </u> |
| .acuum system— vapor    | -          | 1               | -           |                    | 1       | 11  |
| takuum system- sputter  | 1          |                 | 1           | 1                  | 1       | 1   |
| etching system          | -          | _               | -           | -                  | _       | -   |
| screen printing         | 1          | 4               | 2           | _                  | 2       | !   |
| laser trimming          | 1          | 1               | 1           | 1                  | 1       |   |
| continuity tester       | _          | -               | _           | -                  | 1       | -   |
| die attach              | 1          | 2               | 2           | 1                  | _       | 1   |
| tape auto. bonding      | -          | _               | -           |                    | -       | -   |
| 'ump tape auto. bonding | _          | -               | _           | -                  | -       | -   |
| chip carrier bonding    | 2          | -               | 1           | 1                  | -       | 1   |
| inner lead bonding      | 1          | 1               | 1           | 1                  | -       |   |
| outer lead bonding      | i          | 1               | 1           | 1                  | _       | -   |
| wisebond-for chip/wire  | 1          | 1               | -           | 2                  | 1       |   |
| virepull                | 2          | 2               | 2           | 3                  | 1       | 1   |
| inspection              |            | _               | 1           | -                  | -       |   |
| sealing                 | 4          | 2               | 4           | 3                  | 2       |   |
| functional test         | -          | _               | -           | 1                  | 2       |   |
| tault isclation—analog  | _          | _               | -           | -                  | 1       | <u>2</u>  |
| foult isoluti n-digital | -          | _               | -           | -                  | -       | •   |
| loak tests              | 1          | _               | 1           | 1                  | 1       |   |
| temperature cycle       | 2          | 1               | -           | -                  |         |   |
| stabilization bake      | 1          |                 | - 1         | 1                  | - :     | -   |
| hurn-in test            | 2          | <del></del>     | -           |                    | -       |   |
| other, please specify:  | - ;        | <del></del>     | -           | <del></del>        |         | -   |

## Figure 24.

## AUTOMATIC RESPONSES ONLY !

12. Please denote the degree of automation used for the following processes.

 $\underline{\underline{M}}$  = manual;  $\underline{\underline{S}}$  = semi-automatic;  $\underline{\underline{A}}$  = automatic;

|                         | monitoring | load/<br>unload | positioning | process<br>control | inspect      | test                                  |
|-------------------------|------------|-----------------|-------------|--------------------|--------------|---------------------------------------|
| photoresist application | _          | 1               | 1           | -                  | -            | _                                     |
| photoresist exposure    | -          | 1               | 1           | 1                  | _            |                                       |
| photoresist develop.    | 11         | 1               | 1           | 1                  |              |                                       |
| vacuum system- vapor    | 1          |                 | 1           | 2                  | <del></del>  |                                       |
| vacuum system- sputter  | 1          | 1               | 1           | 2                  |              |                                       |
| etching system          | _          |                 |             |                    | -            | -                                     |
| screen printing         | _          | -               | 3           | 1                  |              | -                                     |
| aser trimming           | 4          | 1               | 6           | 4                  | 1            | 4                                     |
| continuity tester       | 4          | 1               | 3           | 2                  | 3            |                                       |
| die attach              | _          | <u>+</u>        | 1           | _                  | _            | -                                     |
| tape auto. bonding      | 1          | 1               | 2           | _ 1                | -            | i                                     |
| cump tape auto. bonding | 1          | 1               | 1           | 1                  | -            | 1                                     |
| Thip carrier bonding    | _          | 1               | 1           | 2                  | _            | -                                     |
| inner lead bonding      | _          |                 | 2           | _                  | _            | _                                     |
| outer lead bonding      |            |                 | 1           | _                  | _            |                                       |
| wirebond_for chip/wire  | 2          | _2              | 6           | 4                  | _            |                                       |
| wirepull                | -          | -               | -           | -                  | <del>-</del> | -                                     |
| inspection              |            |                 | _           | _                  | _            | -                                     |
| sealing                 | _          |                 | 1           | 1                  |              |                                       |
| functional test         | 2          | 1               | 2           | 1                  | 11           | · · · · · · · · · · · · · · · · · · · |
| radit isolation—analog  | -          |                 | _           | -                  |              | i                                     |
| ranit isolation-digital | -          | -               | -           | -                  | _            | :                                     |
| leak tests              | 1          | -               | _           | 2                  | 1            | 2                                     |
| temperature cycle       | 2          | _               | 3           | 4                  | 1            |                                       |
| stabilization bake      | -          |                 | 1           | 2                  | -            | į.                                    |
| burn-in test            | 1          | -               | 1           | 2                  | -            | !                                     |
| other, please specify:  | -          | _               | -           | -                  | -            | -                                     |

13. How is the following data compiled/generated? Check the appropriate box.

|                             | CAD/CAM<br>turnkey | CAD/CAM<br>mainframe | general/TS<br>waintrame | other |
|-----------------------------|--------------------|----------------------|-------------------------|-------|
| vendor die topography       | 2                  | 1                    | 1                       | 4     |
| production planning         | 1                  | 1                    | 4                       | 1     |
| programs for laser trimming | 2                  | 1                    | -                       | 3     |
| programs for device attach. | 2                  | -                    | 2                       | 2     |
| programs for wirebonding    | 1                  | _                    | 2                       | _     |
| configuration control       | 1                  | - 1                  | 1                       | 3     |
| other, please specify:      | _                  | -                    | -                       | -     |

1 self teal

14. How is this data transfered between systems? Check the appropriate box.

|                                | on line      | off line | MANUAL |
|--------------------------------|--------------|----------|--------|
| vendor die topogr <b>ap</b> hy | -            | 4        | 1      |
| production planning            | 2            | 2        | 1      |
| programs for laser trimming    | <del>-</del> | 3        | 1      |
| programs for device attach.    | -            | 3        | 1      |
| programs for wirebonding       | _            | 2        | 1      |
| configuration control          | _            | 3        | 1      |
| other, please specify:         | -            | -        | ] -    |

NO RESPONSE : 3

3. <u>Brief y</u> describe a problem whose solution would be of significant benefit

in the areas of hybrid design and manufacture.

NO RESPONSE : 6

1. team work between divisions

6. replacement for gold metalization

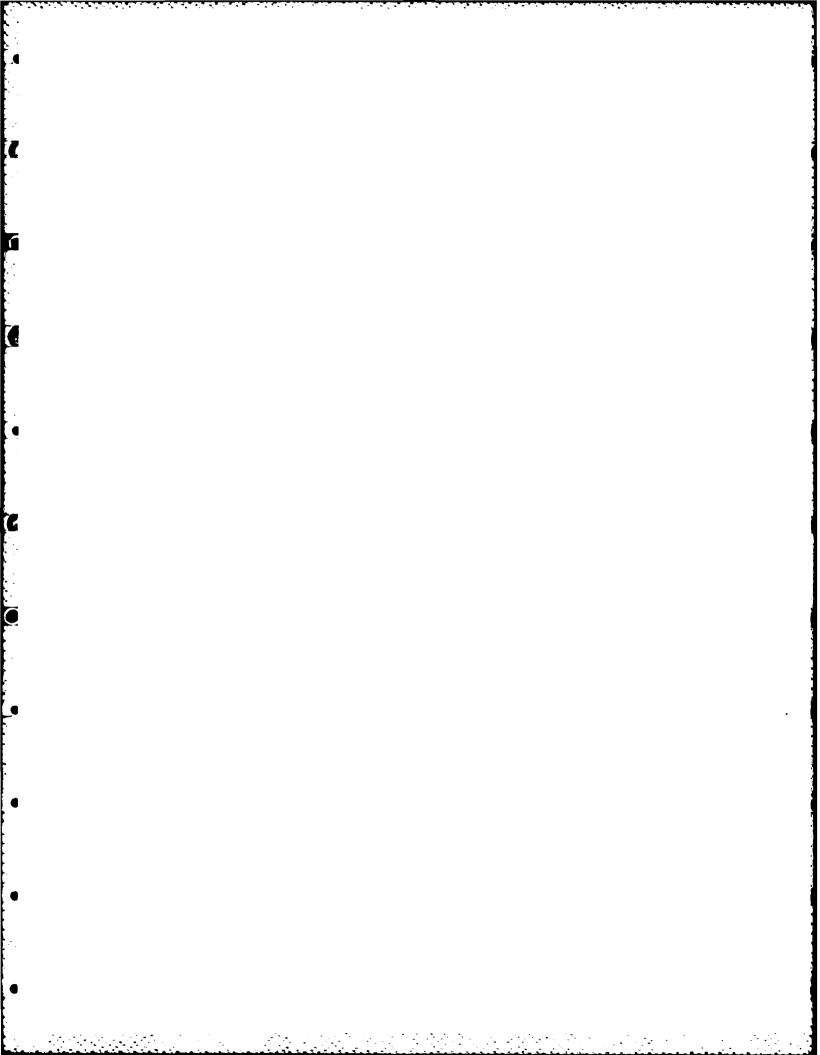
2. automated inspection

- 7. eliminate wirebonding
- 3. automated parts identification
- 8. higher value thin film resist or and
- 4. standardize to chip carriers

- better temperature coefficient-
- 5. develop solid encapsulation to avoid hermetic sealing

16. Would you like to see the results of this survey? yes no Would you consider discussing this survey over the phone? yes no

If the answer is yes please include your name and phone number.



#### - SURVEY SUMMARY -

The response to the industry survey was very limited. Forty questionaires were mailed out. Ten responses were received back. The compilation of the ten responses is detailed in figures 17 through 25. The compiled data is not statistically significant. The identified problems from question 15 were addressed in the Future MAN TECH area of this report if they were of significant depth. The lack of response to the survey may be attributed to industry disinterest, a natural desire not to disclose a percieved competitive advantage, and the length of the survey itself. The Proceedings of the Fourth MTAG Hybrid Workshop-Conference indicates that only 24% of the attendents viewed HICADAM as a high priority MAN TECH project, which supports the lack of response to the survey.

#### -FUTURE MAN TECH AREAS -

A roadmap for future MAN TECH efforts is presented. The candidate tasks identified are directed towards the cost effective advancement of an integrated and automated hybrid microelectronics manufacturing facility.

Each task represents an integral building block in achieving the automated factory yet does not have any current or planned MAN TECH expenditures.

The majority of these tasks are directed at integration aspects for interfacing the design and manufacture of hybrids.

The tasks were identified as follows. An overview of current design and manufacturing activities was developed. Problem areas were identified through this overview, through an industry survey (which may not be statistically significant), and through discussions with design and manufacturing personnel. These areas were compared with a compilation of future and ongoing MAN TECH projects. The candidate tasks were selected where no funding was planned for an identified problem. (refer to figure 36 for compilation)

Current and planned MAN TECH projects are directed at materials and equipment advancements or at specific end item technologies. These expenditures will reduce production costs and lead towards an automated factory. The current and planned funding programs will not lead to the viable integration of this automated factory. While the automation of the specific processes is sought the ability for these automated machines to communicate with each other and with other computers is not assured.

The proposed roadmap has two added thrusts. First, the integration of the CAD database and the CAM database is pursued. Second, the ability for inter-machine/computer communication is pursued. Integration is not as glamorous as automation but its lack can eliminate the synergy of automation.

Hybrid Microelectronics Database Specifications

The hybrid database specification is the framework for establishing a CAM database during the design phase in the life cycle of a hybrid. This database structure can be viewed as being empty at the start of the design process. As the hybrid is designed this structure becomes populated with information (electrical, physical, and logical) about the hybrid. The structure, when fully populated, contains the information required to support automated production facilities and the information is filed to provide the efficiency required for real time applications.

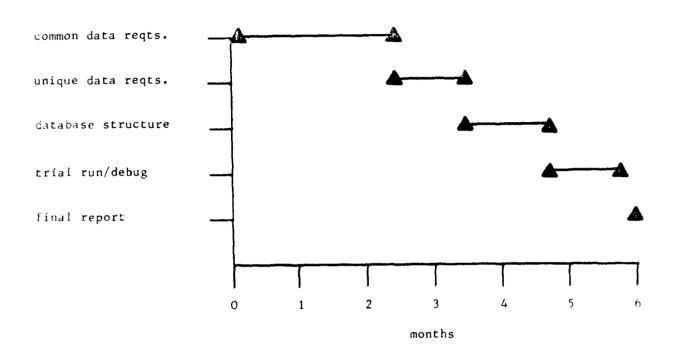
The first step is to map the data needs, both common and unique, required by specific manufacturing processes and support functions. This mapping specifies data content, where this data is required, and where this data is generated. This analysis aids in defining input and output requirements.

The database structure can then be established. This structure must permit the efficient filing of common and unique data. The type of structure (hierarchical, network, or relational), the field lengths, and data formats must be selected. The files should be organized around IGES (interim graphics exchange specifications) formats.

Finally, the documentation for this database specification must be developed. This documentation should contain sufficient written and pictorial information so that the end user can understand the database structure and its applications.

Future MAN TECH projects would be approached so that this database specification could be used to support the automation of manufacturing processes. This will ensure that automated equipment can interrogate the same database and will ensure the transportability of automated processes.

FIGURE 26.
HYBRID DATABASE SPECIFICATIONS



## Estimated Budget :

labor......\$67,200 \*
computer time.. 22,500 #
travel...... 3,300
total costs...\$93,000

# 150 hours (not CPU time, bid rate at \$150/hr)

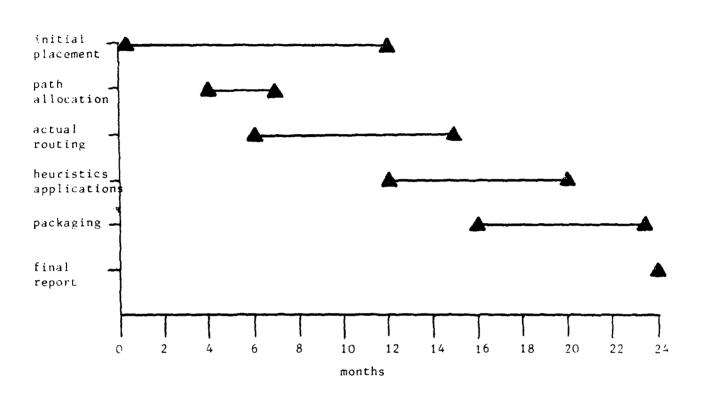
<sup>\*</sup> one man year

Component Placement and Routing Algorithm

As circuit densities increase placement and routing algorithms become very important. They become important from a design efficiency and from a producibility standpoint. Current component placement and routing algorithms are either modified printed wiring board or modified integrated circuit algorithms. These are altered, albeit suboptimally, to consider such factors as maximum flywire lengths, edge connections, vias which do not traverse completely through the substrate, and other important physical characteristics of a hybrid. As routing algorithms operate more efficiently when used with a specific placement algorithm they should be developed simultaneously.

This candidate task will establish a routing algorithm, in tandem with a placement algorithm, which specifically addresses hybrid circuits. It must consider parameters such as those mentioned above as well as crossovers, components that are designed into the circuit layers, and multi-layer hybrids. These algorithms must deliver a database which is complete and consistent enough to support automated manufacturing, inspection, and test equipment. These algorithms must also be compatible with several types of computer support systems.

FIGURE 27.
COMPONENT PLACEMENT AND ROUTING ALGORITHMS



### Estimated Budget:

labor......\$560,000 \*
computer time.. 140,000
travel...... 5,000
total cost....\$565,000

\* initial placement... 2 man years path allocation.... 1/2 man year actual routing..... 1 1/2 man years heuristic applications ... 2 man years packaging...... 2 man years

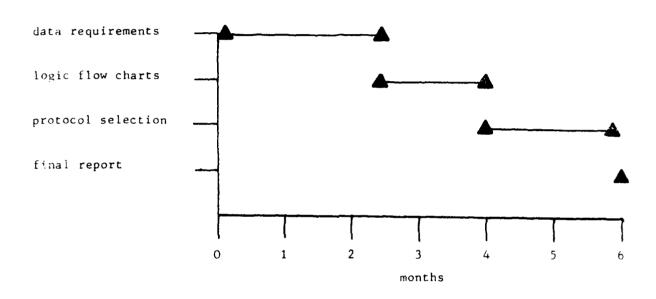
## Physical Communications Interfaces

The purpose of this candidate task is to develop the specifications required for communications within an integrated manufacturing environment. This communication would occur between the digital engineering systems, the manufacturing information systems, and the specific computer aided manufacturing processes.

Several entities would be addressed. First, the data needs for each specific manufacturing operation must be defined (as per the database specification). Then these data needs must be melded into a generic logical flow of information. Protocol aspects must then be addressed. Protocol is the formal data transfer specifications (examples are RS232, RS449, IEEE488, BISYNC, X2.5, etc.). Parameters such as physical distance, serial or parallel transmission, noise and interference tradeoffs, the desired rate of data transmittal, error checking algorithms, and costs need to be defined.

The output from this project would be twofold. First, a generic logical information flow for computer aided hybrid manufacturing will be defined. Secondly, a suitable protocol will be established. This will ensure that future MAN TECH efforts are transportable and can be integrated into an automated factory in a timely and cost effective manner.

FIGURE 28.
PHYSICAL COMMUNICATION INTERFACES



## Estimated Budget :

labor.....\$67,200

travel..... 2,800

total cost..\$70,000

#### Automatic Parts Identification

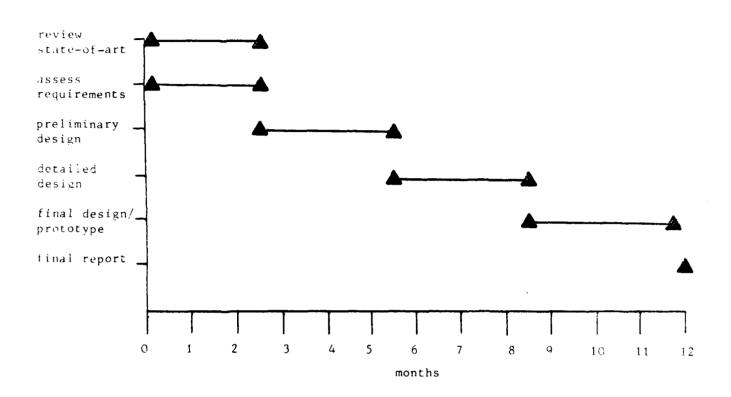
Automated substrate and module identification are important and necessary requirements if the high mix-low volume hybrid manufacturing facilities are to become significantly automated. The automation of the identification activity will accomplish several objectives. It will allow the automatic download of process control software to the specific manufacturing, inspection, or test work station. It will ensure a real time update of the associated MIS systems, such as production control and part history tracking. It will eliminate operator induced errors from manually entering identification data. It will serve as an integral subset of a closed loop, self checking automated material handling system.

Characteristics of an automated parts identification system are to include :

- compatibility between substrate and module identification
- compatibility with the manufacturing processes for hybrids
- useable by work stations and material handling equipment
- versatile communications interface with host computing systems

The automation of parts identification is an important building block in support of an automated factory. It will reduce indirect labor costs, eliminate operator error, and can be used in monitoring and controlling an automated material handling system.

FIGURE 29.
AUTOMATIC PARTS IDENTIFICATION SYSTEM



## Estimated Budget\*:

labor.....\$140,000
travel..... 10,000
total cost..\$150,000

 $<sup>\</sup>ensuremath{^{\pm}}$  prototype equipment costs not included

### Automated Material Handling System

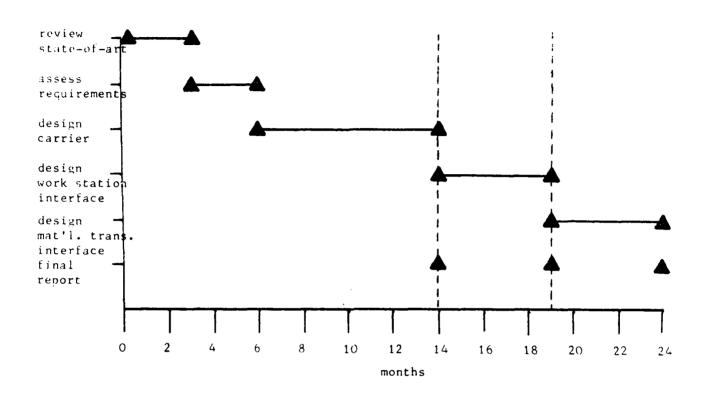
Automation of material handling activities in hybrid circuit manufacturing is one of the major milestones in achieving an automated factory. An undertaking in this area should be an integrated, multifacted effort. Specific activities to be addressed are:

- material handling between work stations
- material handling between work station and the material handler
- material handling at each specific work station

The first milestone will be to develop a substrate/module carrier system. This system must offer protection to work-in-process items, must be compatible with all work stations, must be impervious to damage from the hybrid manufacturing processes, and must interface with the automatic parts identification systems.

Once the carrier system has been designed a two-pronged effort can be undertaken to integrate the carrier system with an automated transfer system for movement between work stations and to integrate the carrier with material handling requirements at each specific work station. This integration effort will ensure the transportability of the automated material handling system. Future MAN TECH equipment advancements would be designed around the use of the carrier system.

FIGURE 30.
AUTOMATED MATERIAL HANDLING SYSTEM



#### Estimated Budget \*:

| labor\$       | 168,000   |
|---------------|-----------|
| travel        | 4,000     |
| phase 1 cost. | \$172,000 |
| labor\$       | 44,800    |
| travel        | 1,200     |
| phase 2 cost. | \$46,000  |
| labor\$       | 56,000    |
| travel        | 2,000     |

total project cost.....\$276,000

<sup>\*</sup>prototype equipment not included

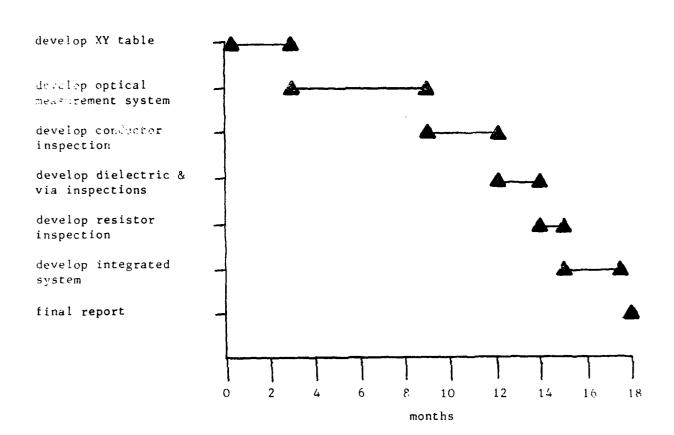
#### Automated Substrate Inspection

The current practice of manually inspecting the substrates for hybrids is very operator dependent for success. The operator must track the substrate movement, and make a subjective judgement as to pass/fail conditions. As circuit densities increase and multi-layer hybrids become more common this manual process will not adequately perform its task.

This candidate task would automate this process. The substrate would be mounted on an XY table which is programmable. As the substrate is cycled through an automatic sequence of movements an optical measurement system would compare the actual topography with the topography of a digitized database. This comparison would result in a pass or fail decision which would be printed out with the XY coordinate of the discrepant area.

This project would increase the uniformity and consistency of the substrate inspection process. Automation would also decrease the time spent undergoing an inspection. The equipment should be made compatible with future automation projects which address the screen printing process.

FIGURE 31.
AUTOMATIC SUBSTRATE INSPECTION



#### Estimated Budget\*:

labor.....\$210,000 travel.... 5,000 total cost..\$215,000

\*prototype equipment costs are not included

Microbridge Production Technology

The traditional bonding of gold wire or ribbon via thermocompression or ulrasonic techniques does not compliment the fine line spacings offered by the use of thin film fabrication technologies. This type of interconnection technology does not adequately support the advent of very high speed hybrid circuits.

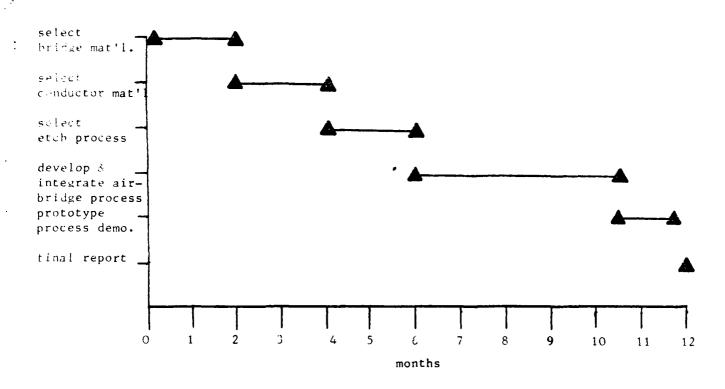
The purpose of this future MAN TECH project is to develop and demonstrate the microbridge technology applications as an interconnection technique on thin film substrates in a mass production environment. (reference to the unbudgeted Navy project DNA-006XX) Microbridges are thin film plated crossovers. They may be fabricated as below:

- ]) create the interconnection bridge structure
- 2) plate the bridge structure with a conductive material
- 3) remove the bridge structure, leaving the conductor bridge
  This process will be more complex to control but will utilize the equipment
  available for additive thin film processing.

The additional costs and complexities of microbridge technologies are outweighed by the advantages it offers. These include:

- batch processing as opposed to bonding one wire at a time
- the process will result in very uniform interconnections
- the interconnection fabrication will be more consistent
- total costs will be reduced
- enable the interconnection of very fine thin film lines
- provides better and more controllable interconnection techniques to support very high speed hybrids

FIGURE 32.
MICROBRIDGE PRODUCTION TECHNOLOGY



#### Estimated Budget\*:

labor.....\$140,000 travel..... 3,000 materials... 25,000 total cost...\$168,000

\*prototype equipment costs are not included

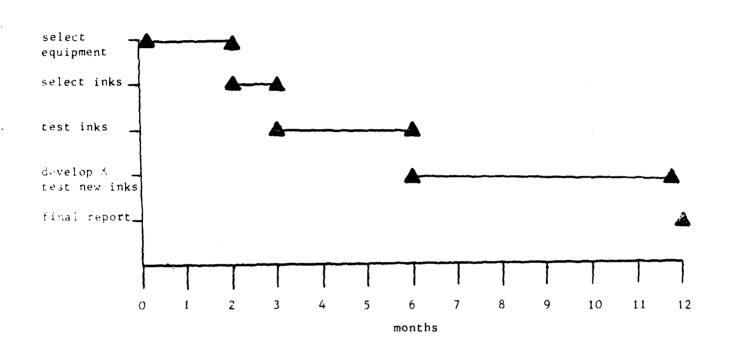
Thick Film Ink Characterization for IR Furnaces

The purpose of this candidate task is to analyze, characterize, and, if necessary, develop thick film inks to be used in conjunction with IR furnaces. The development of thick film inks which are compatible with the IR firing environment will result in a production process which has:

- a faster throughput rate
- lower equipment costs
- reduced floor space requirements
- reduced power consumptions

Thick film inks from various manufacturers will be screened at different levels of thicknesses and then subjected to a 1,000 hour test. The results will then be tabulated and analyzed. The strengths and weaknesses of currently available inks will be assessed. Compatible inks and their applications will be presented. The development of thick film inks, or recommendations for ink improvements, will be conducted as required.

FIGURE 33.
THICK FILM INK CHARACTERISTICS



#### Estimated Budget :

labor.....\$140,000
materials... 60,000
travel..... 4,000
total costs.\$204,000

Semi-Automatic Die Probe System for Prescreening Tests

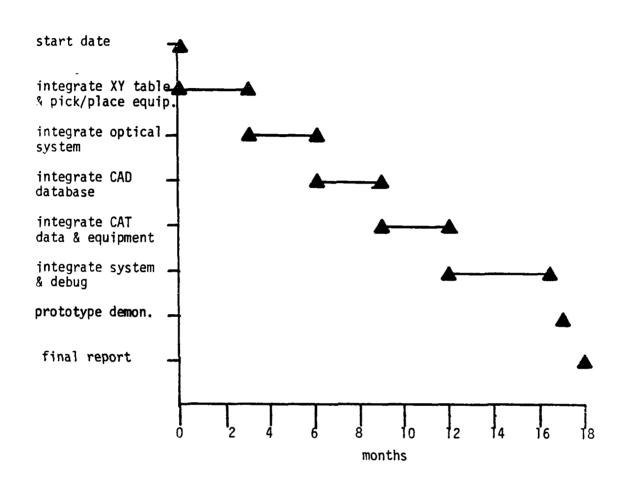
The final cost of a hybrid circuit is greatly influenced by the manufacturing expenses incurred in producing it. Rework caused by the failure of inadequately pre-tested die can be a major cost contributing factor. The purpose of this future MAN TECH project is to develop a semi-automated probe test system for prescreening die.

This system would incorporate several modifications to a manual probe test station. These modifications include:

- automatic pick and place mechanisms
- automatic XY table system
- optical alignment system
- CAD database interfaces
- CAT database interfaces
- test equipment and data recording equipment integration

This automated system would test die directly from waffle packs. As such this system would have maximum transportability among manufacturers. The ability to prescreen die via probing at elevated temperatures will insure the maximum benefits from automating the assembly processes for hybrid microelectronics.

FIGURE 34.
SEMI-AUTOMATIC PROBE TEST SYSTEM



#### Estimated Budget:

| total cost\$ | 245,000 |
|--------------|---------|
| material     | 30,000  |
| travel       | 3,000   |
| labor\$      | 212,000 |

Automated Camera and Test Probe Configuration

Existing fault isolation methods typically involve manual probing of the assembled substrate. The very delicate nature of the assembled substrate, especially when chip and wire technology is used, and the small area available for probing make this process slow and expose the substrate to increased chances of damage.

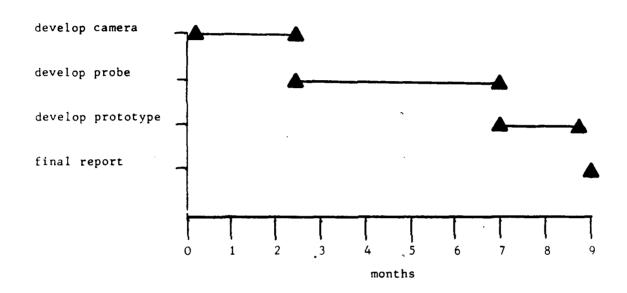
The output of this project would be an automated probe integrated with a video camera machine. This machine would be driven with information from several sources which are:

- the results of prior functional tests
- specific fault isolation programs
- geometric information derived from the engineering database
   The camera would guide the probe and view the probed areas for evidence
   of physical discrepancies.

The camera and probe would be mobile as opposed to moving the substrate. This is required by the electrical needs of high speed or electrically sensitive circuits.

This project would address the mechanical requirements and the software integration aspects to support the mechanics rather than the specific fault isolation software needed.

FIGURE 35.
AUTOMATIC CAMERA AND TEST PROBE SYSTEM



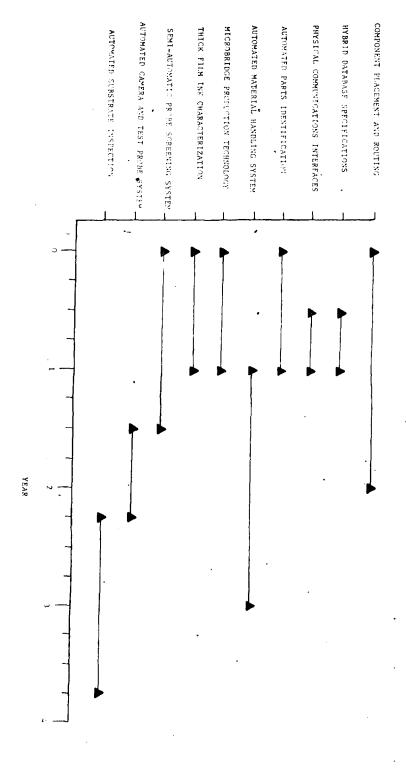
#### Estimated Budget\*:

1abor.....\$100,800 travel..... 2,200 materials... 2,000 total cost..\$105,000

\*prototype equipment costs are not included

FIGURE 36.

COMPILED SCHEDULES



### APPENDIX A HICADAM ARCHITECTURE

A HICADAM System architecture is proposed. This architecture reflects those generic functions, inputs, outputs, mechanisms, and controls utilized in the design and manufacture of hybrid circuits. The interfaces of a CAD/CAM system and an MIS system are reflected on the node tree diagram.

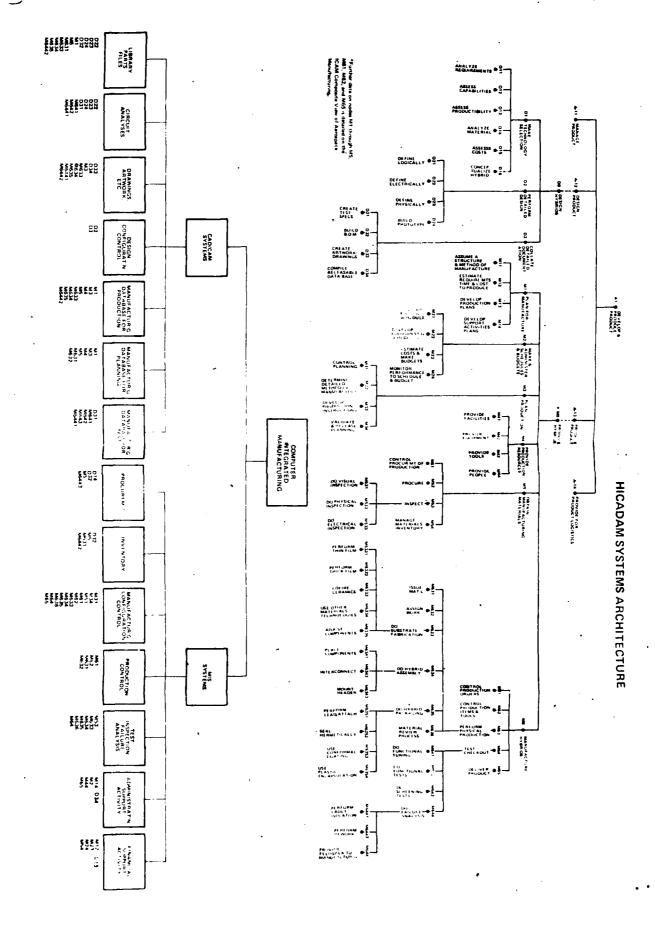
Hybrid design and manufacturing processes and interfaces are high-lighted. The processes as depicted were presented to and critiqued by other operating divisions of Hughes Aircraft and by the Hybrid Commodity Group in support of the ECAM MAN TECH. (ECAM is Electronics Computer Aided Manufacturing and is being conducted by Battelle Labs.) The ICAM IDEF<sub>O</sub> modeling methodology was utilized in drafting the architecture.

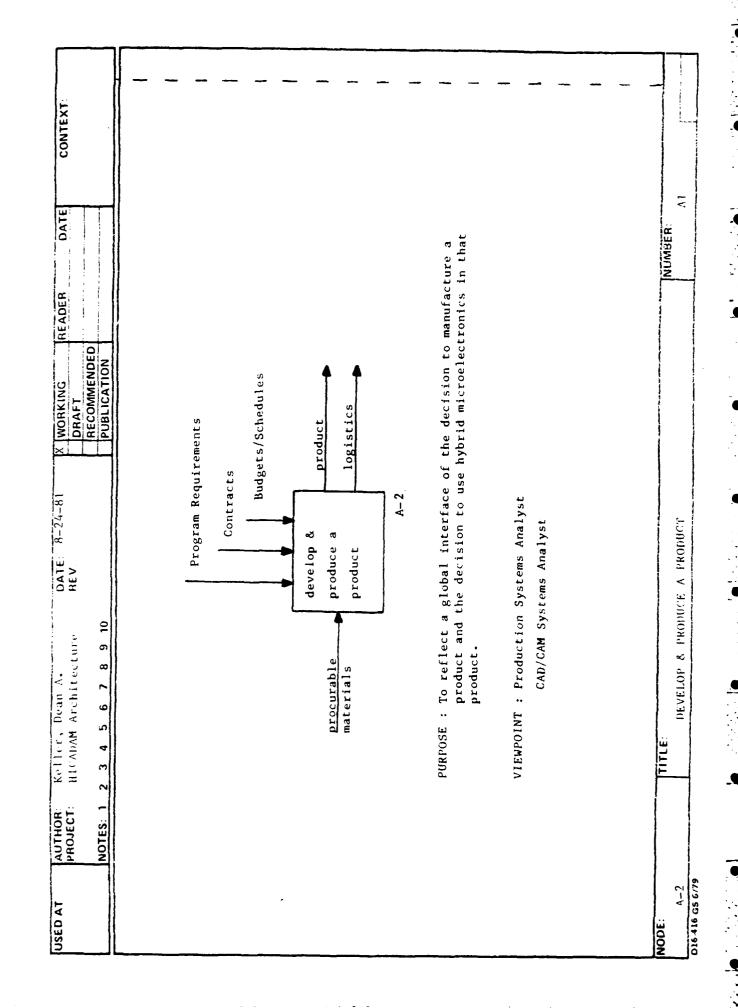
The design activity has been decomposed into three generic activities. These activities are technology selection, detailed design, and detailed documentation.

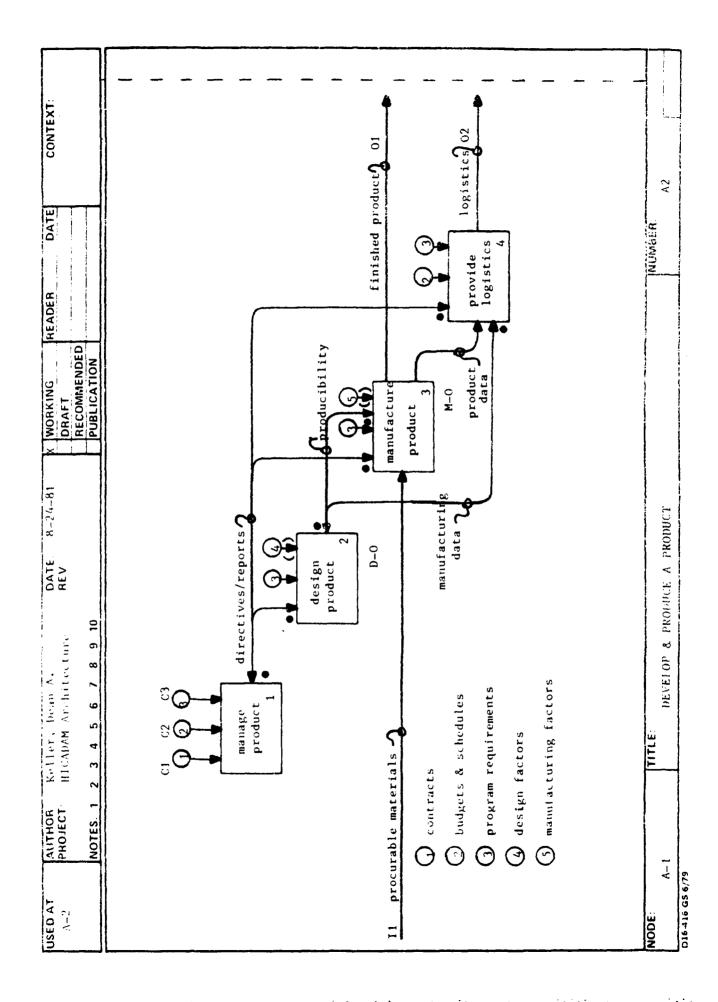
Procurement of the necessary production resources is briefly illustrated.

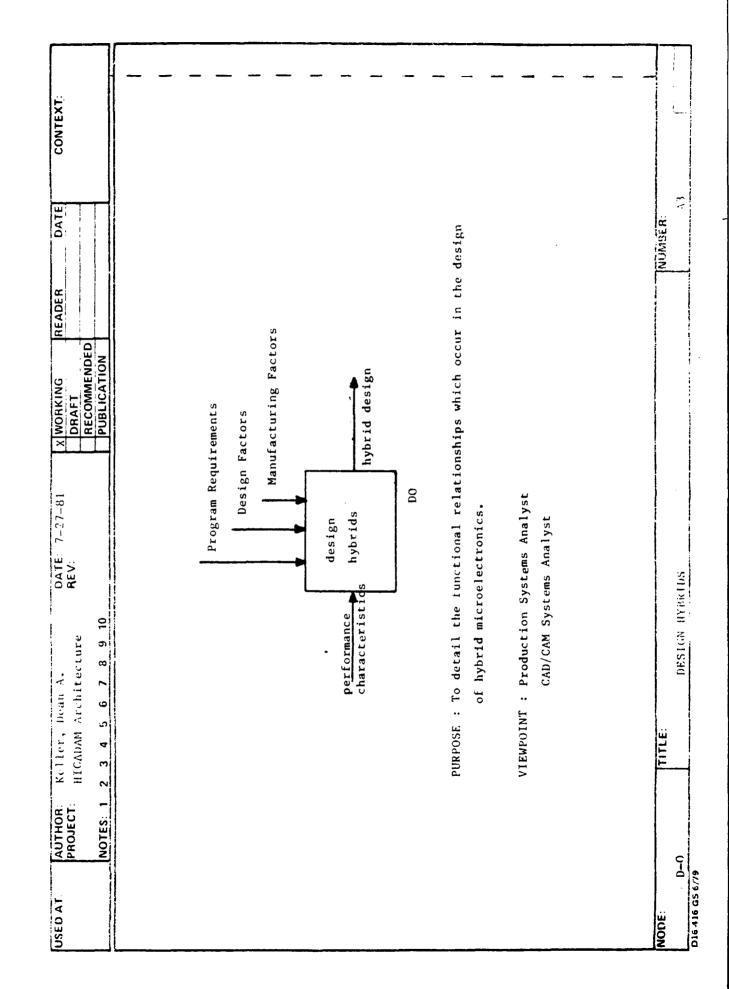
A detailed analysis of these areas is available in the ICAM Composite View of Aerospace Manufacturing.

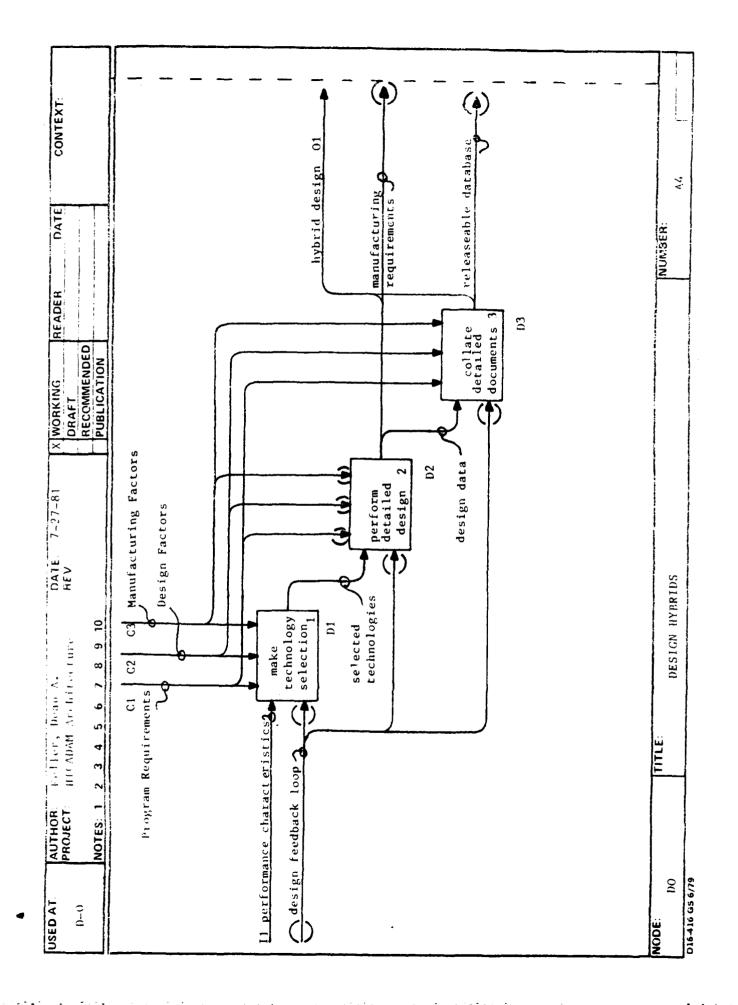
The manufacturing function has been decomposed into six basic areas. These activities reflect the interfaces of quality, test, and the various production technologies (such as thin film, thick film,..., placement, packaging, etc.). Specific illustrations of process flows are given in the main body of this report.

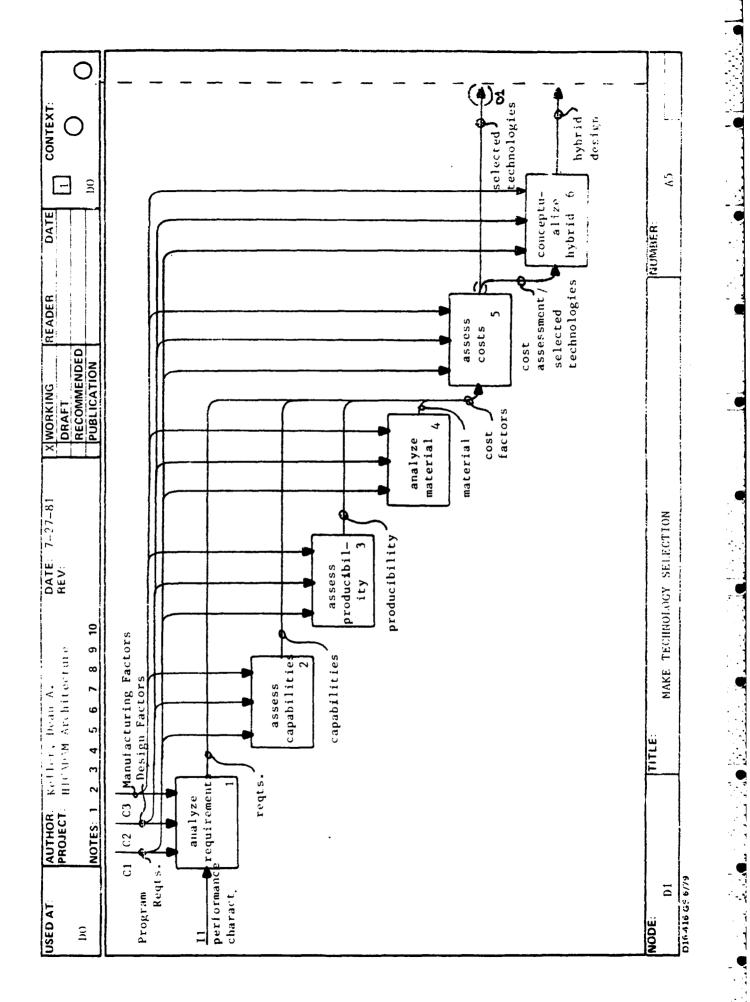


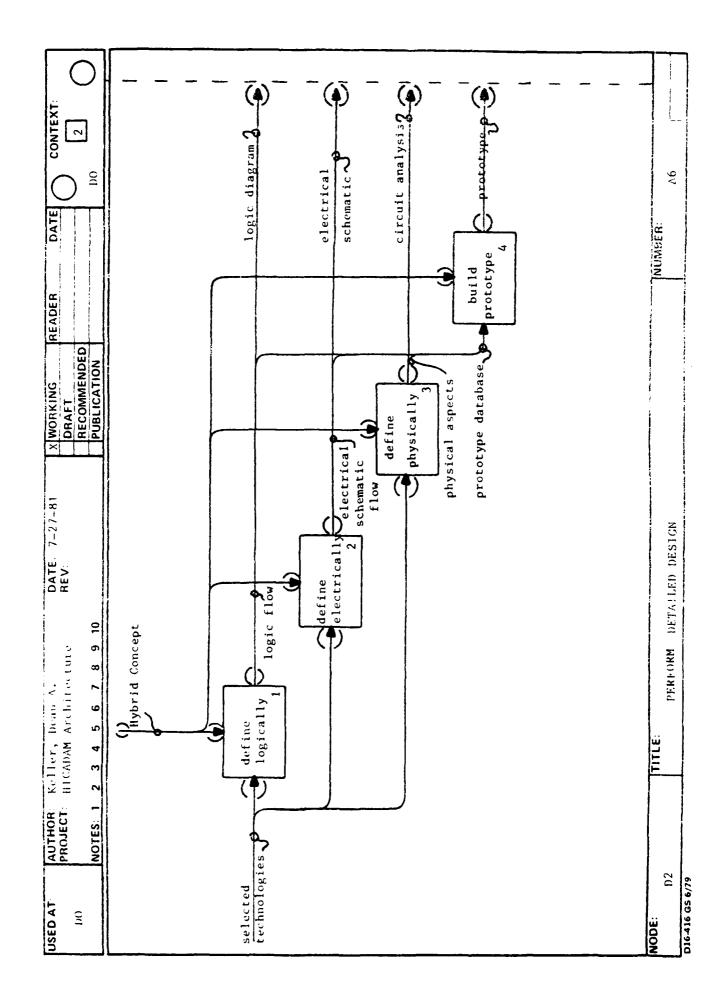


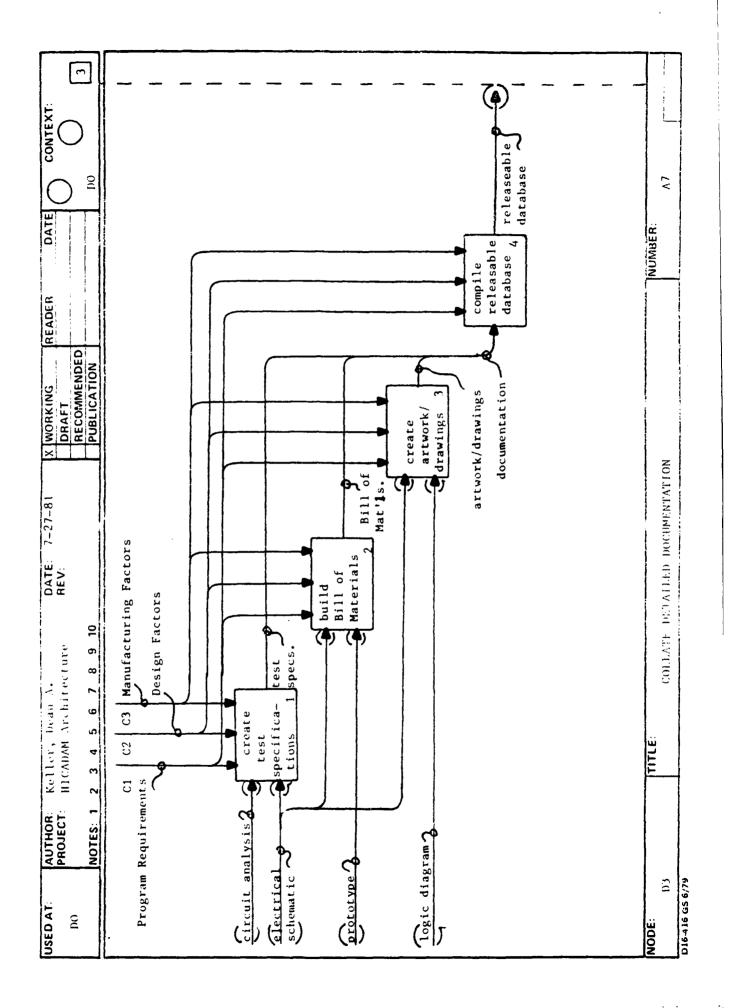




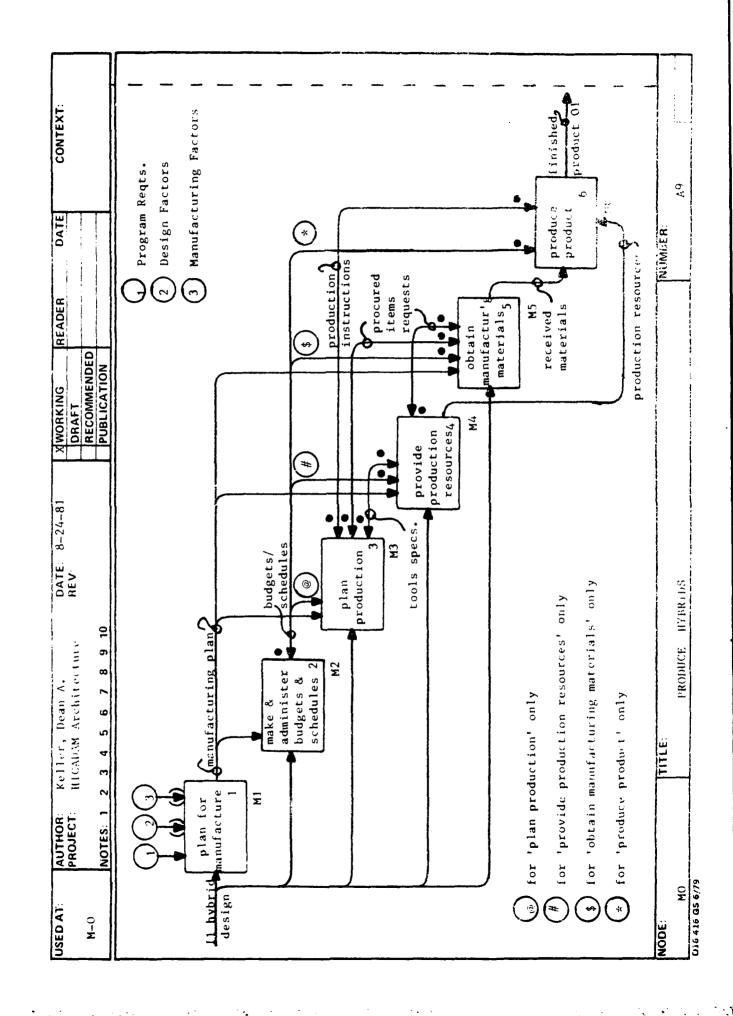


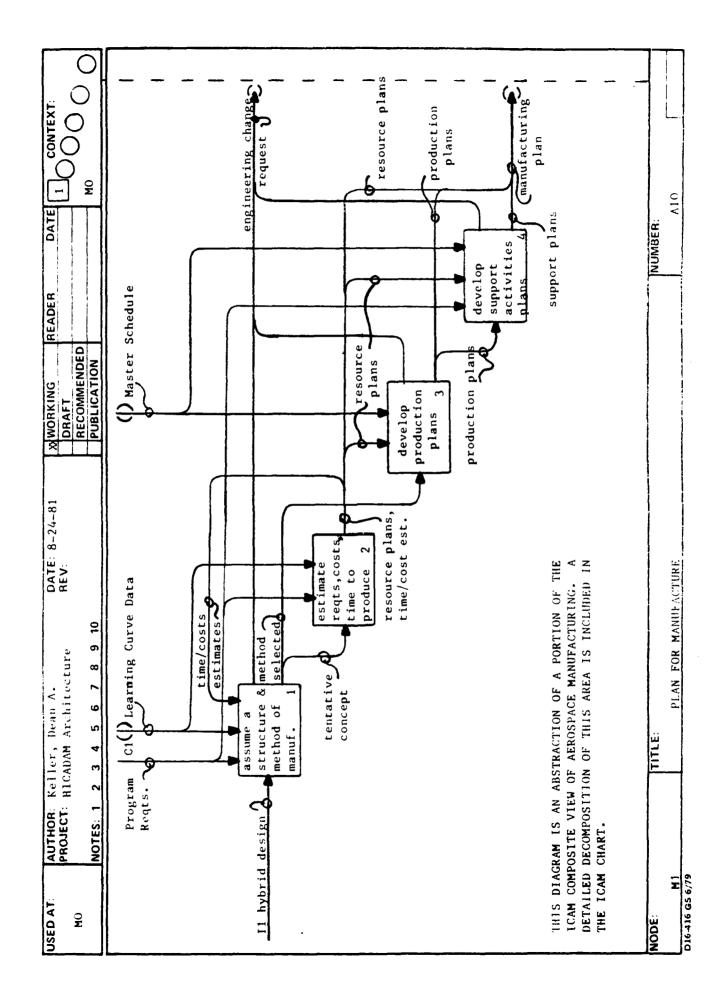




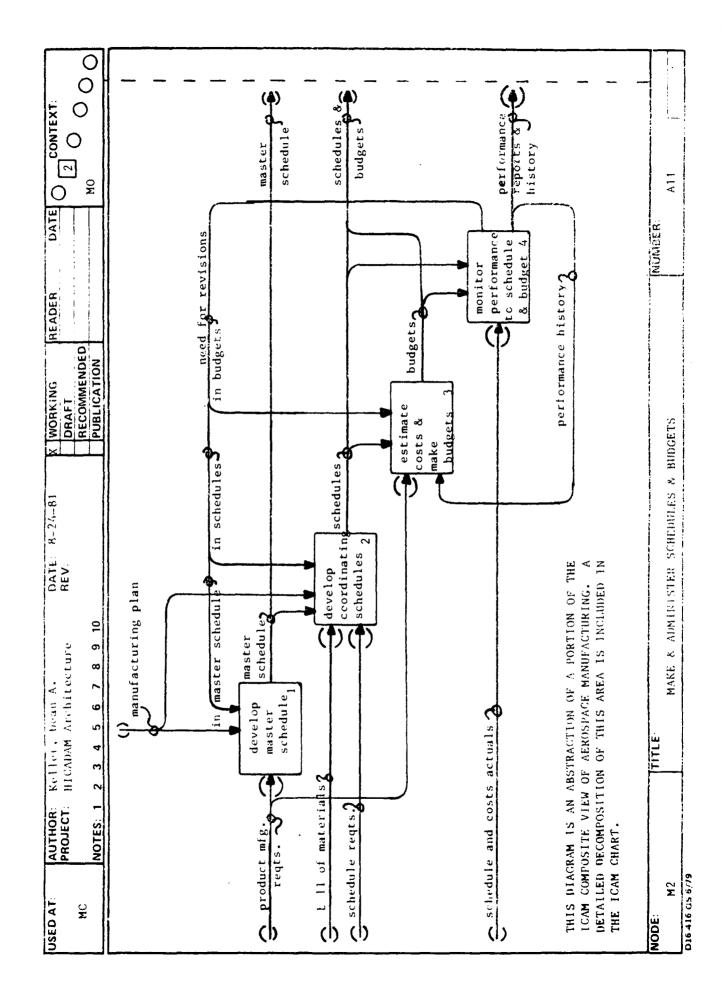


| USED AT.                              | AUTHOR<br>PROJECT | Keller, Dean A.<br>HICADAM Architecture | DATE: 8-24-81<br>REV:                        | XWORKING READER DRAFT   | DATE       | CONTEXT:   |
|---------------------------------------|-------------------|---|--|---|------------|------------|
|                                       | NOTES 1           | 2 3 4 5 6 7 8 9 10                      |  | PUBLICATION   |            |            |
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|                                       |                   |   |  |   |            |            |
|                                       |                   |   | Program Requirements                         | quirements  |            | -          |
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| ····                                  |                   |   | — — — — — — — — — — — — — — — — — — —        | Manufacturing Factors   |            |            |
|                                       |                   | hybrid design                           | produce                                      | completed hybrids   |            | andria and |
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|                                       |                   | CAD/CAM Sys                             | Systems Analyst                              |   |            |            |
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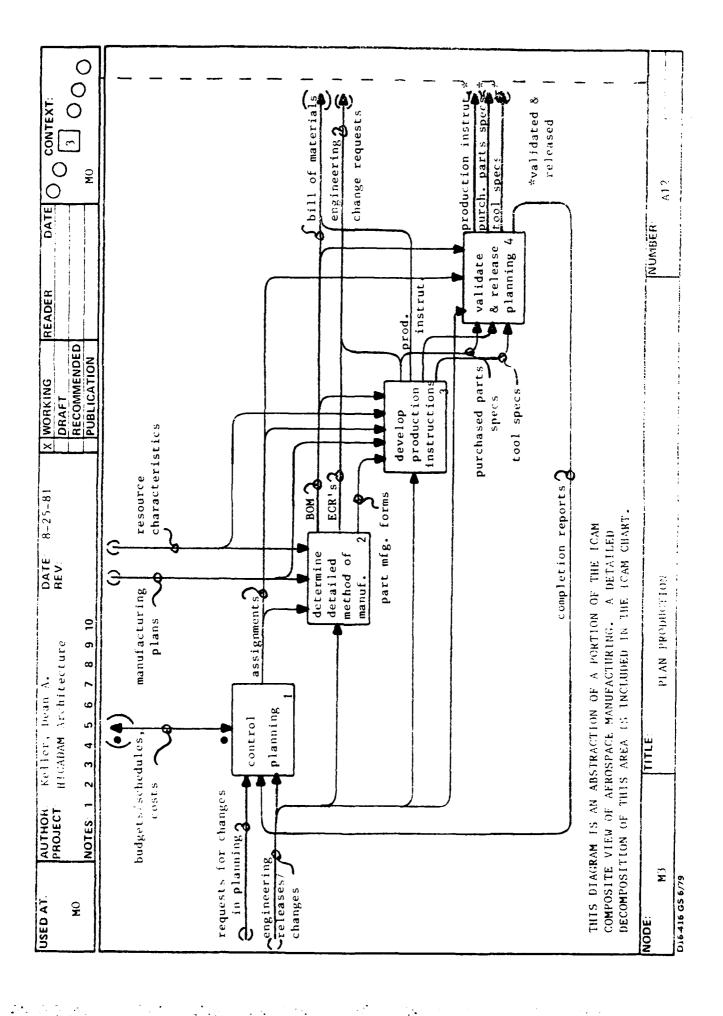


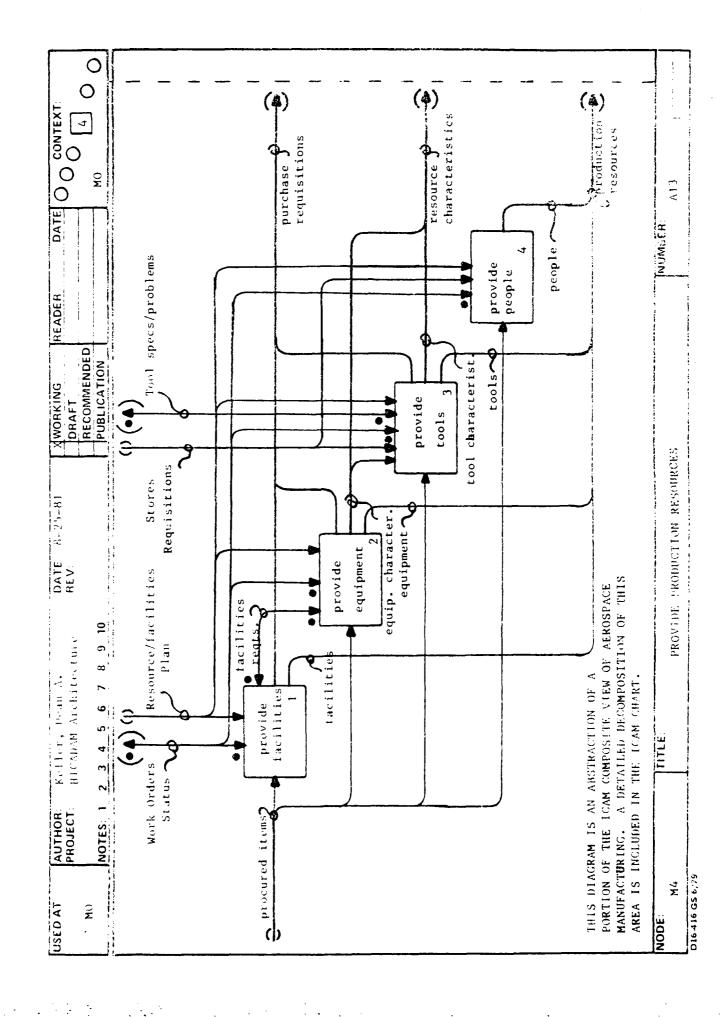
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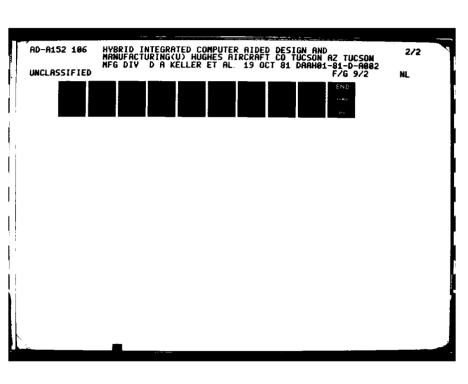


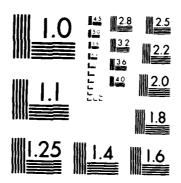
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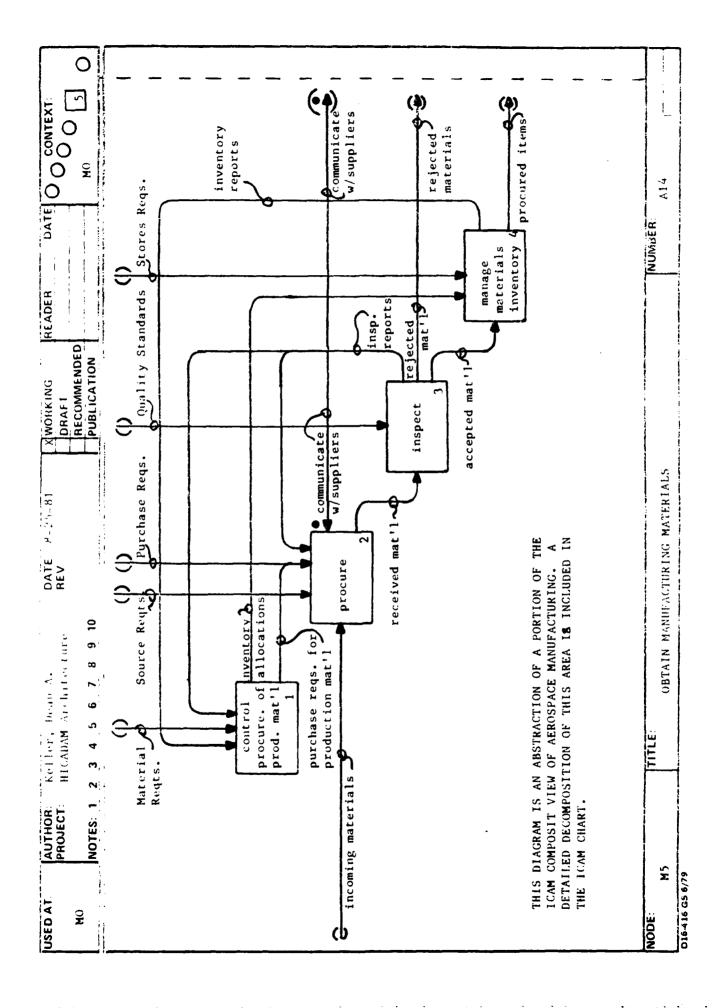




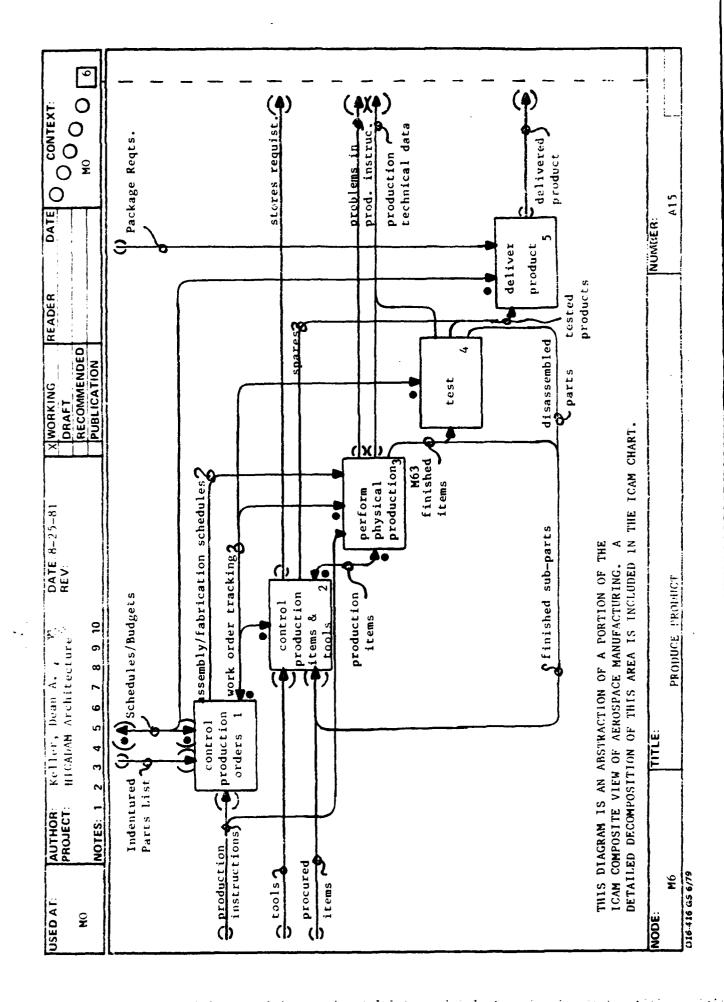


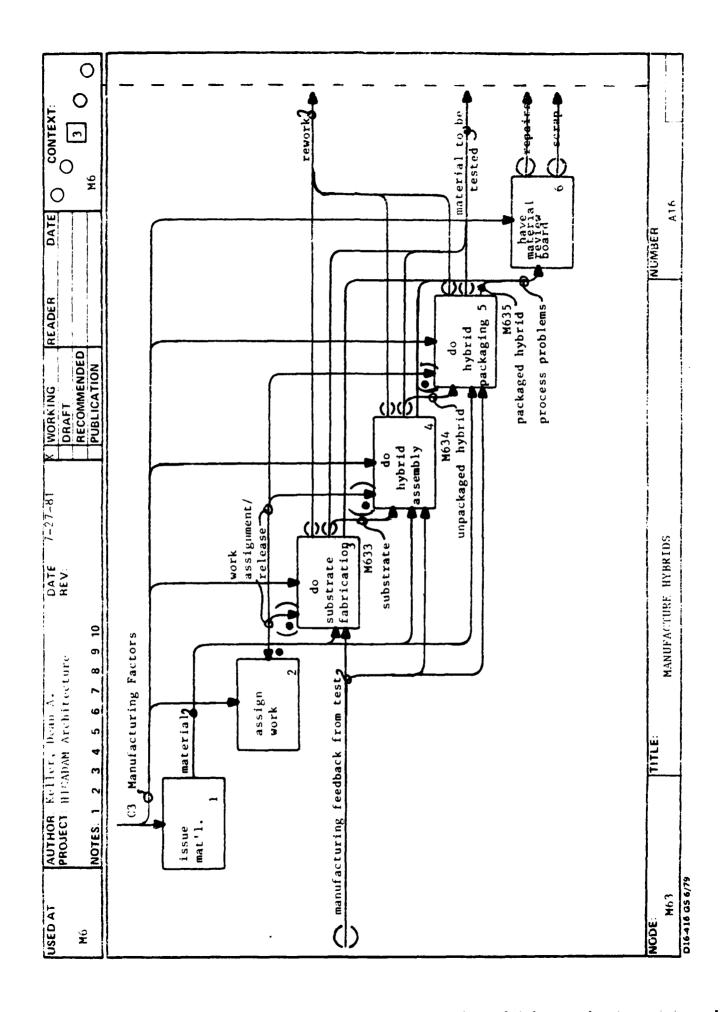


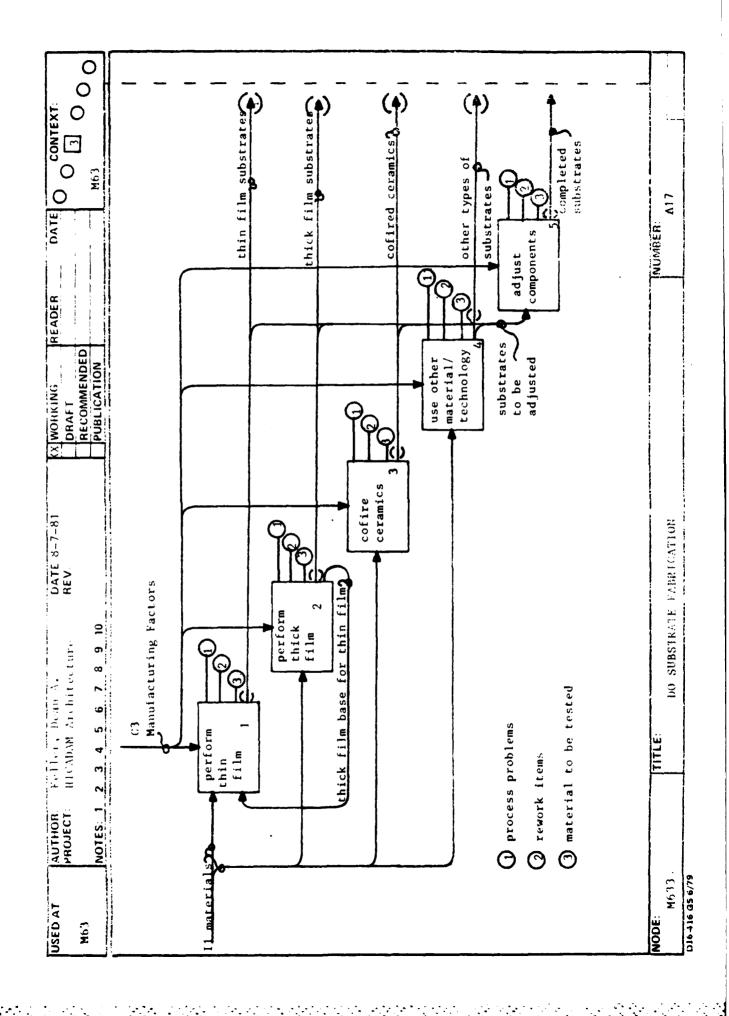
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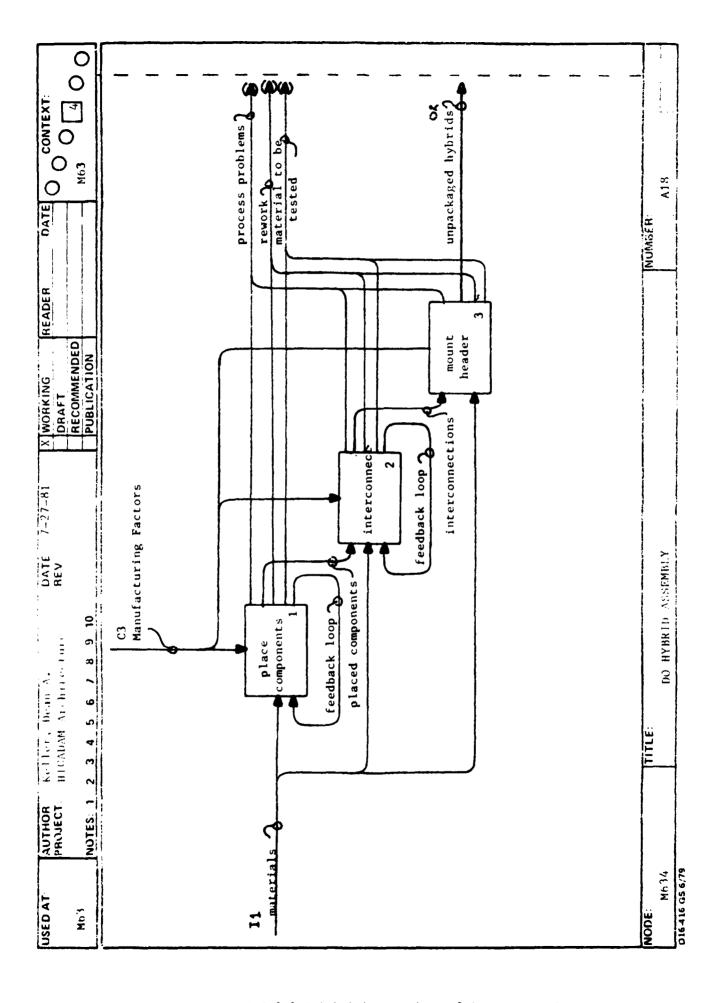


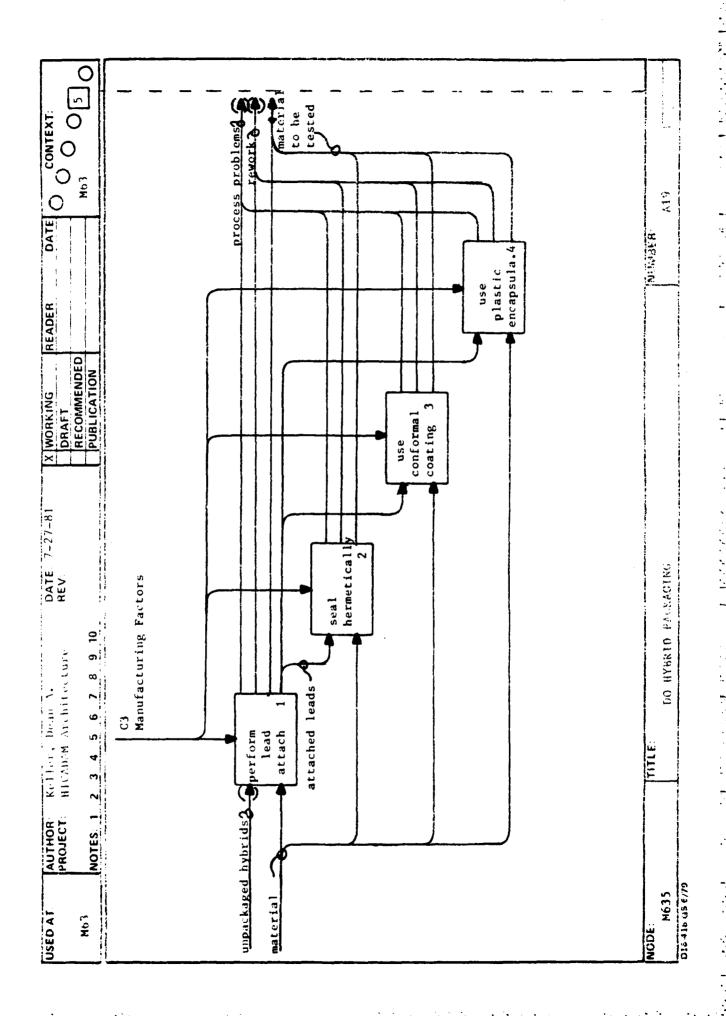
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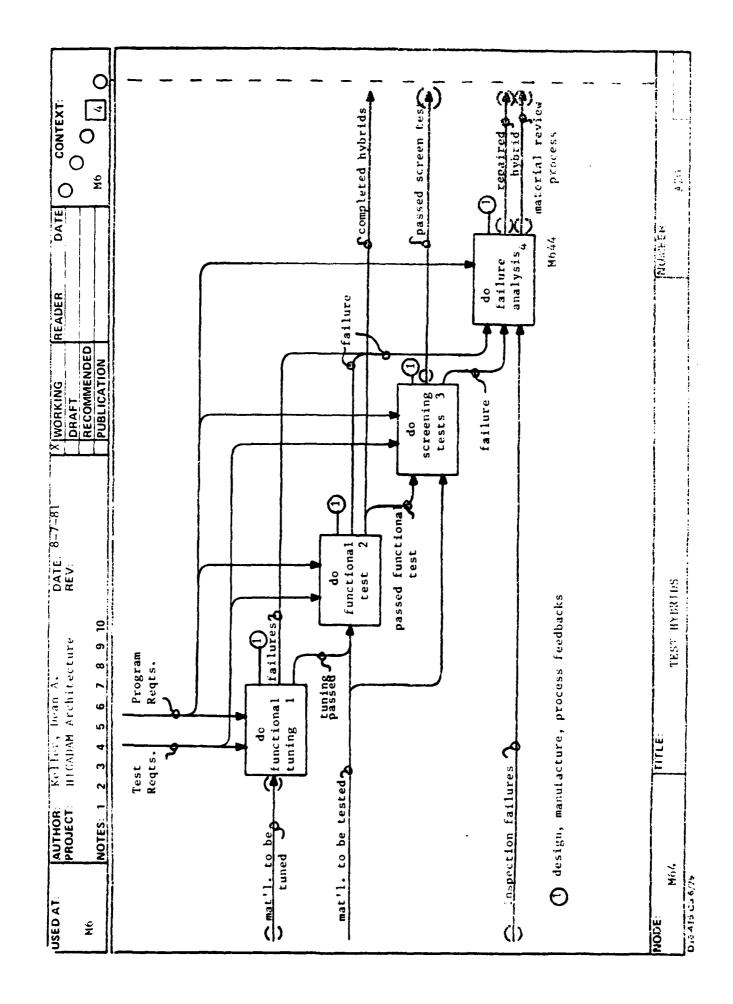




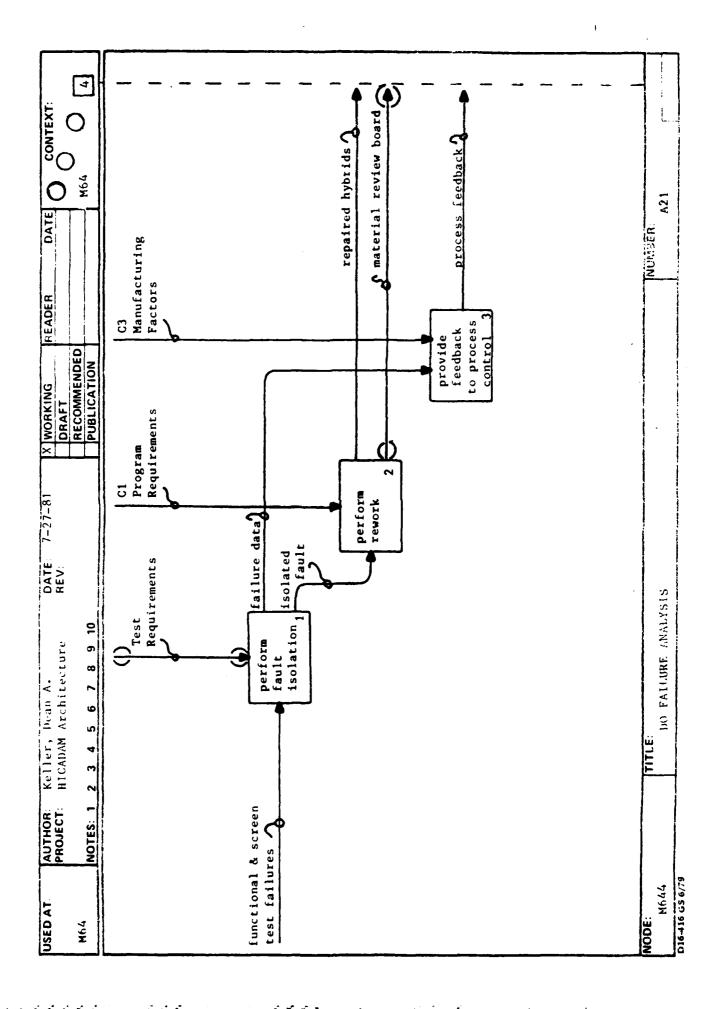








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